

Efficient layout for silicon quantum dot spin qubits

Sophie Rochette, M. Rudolph³, A.-M. Roy², M. J. Curry^{3,4},
G. A. Ten Eyck³, R. P. Manginell³, J. Wendt³, T. Pluym³, S. M. Carr³, D. Ward³,
M. P. Lilly^{3,6}, M. S. Carroll^{3,4} and M. Pioro-Ladrière^{1,2,7}

June 7th 2017

12th Canadian Quantum Information Student's Conference
Orford, Québec, Canada



1



UNIVERSITÉ DE
SHERBROOKE

2



Sandia
National
Laboratories

3



4



5



7



6

Fonds de recherche
sur la nature
et les technologies

Québec



**CRSNG
NSERC**

State of the art for Si quantum dot spin qubits

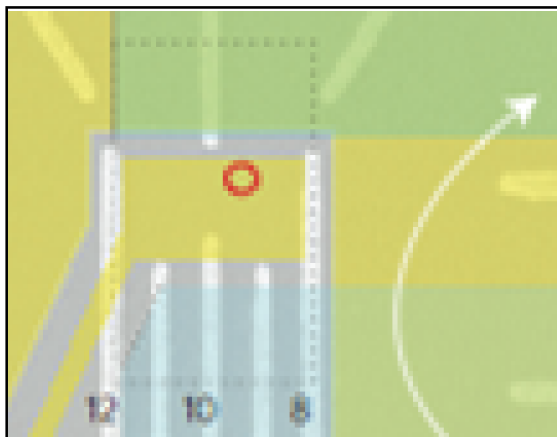
Single qubit gates

Kawakami *et al.*, 2014

Si/SiGe (natural)

Fidelity: 99 %

Micro-magnet (EDSR)

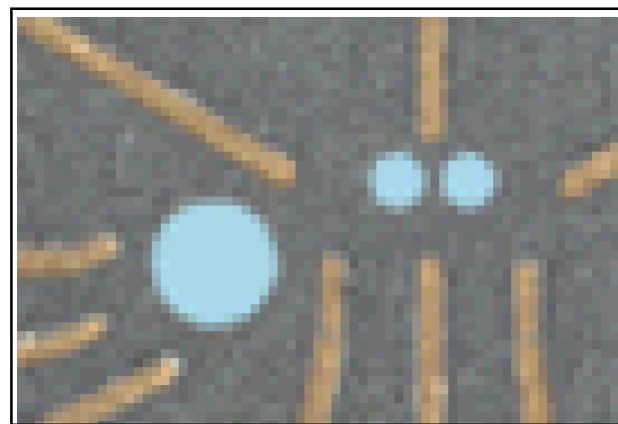


Takeda *et al.*, 2016

Si/SiGe (natural)

Fidelity: 99.6 %

Micro-magnet (EDSR)

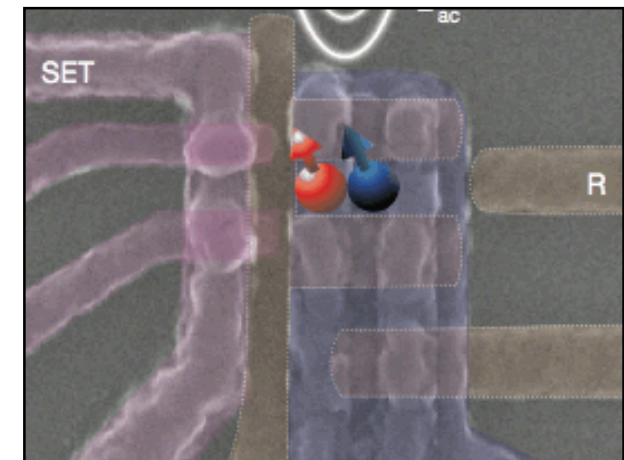


Veldhorst *et al.*, 2014

MOS (Al), Si 28

Fidelity: 99.6 %

Transmission line (ESR)



Large QDs array



Zajac *et al.*, 2016

Si/SiGe

9 QDs

Good reproducibility for
charging energies and
orbital energies

Two-qubit gates

Veldhorst *et al.*, 2015

MOS (Al), Si 28

Fidelity: < 90 %



Presentation structure

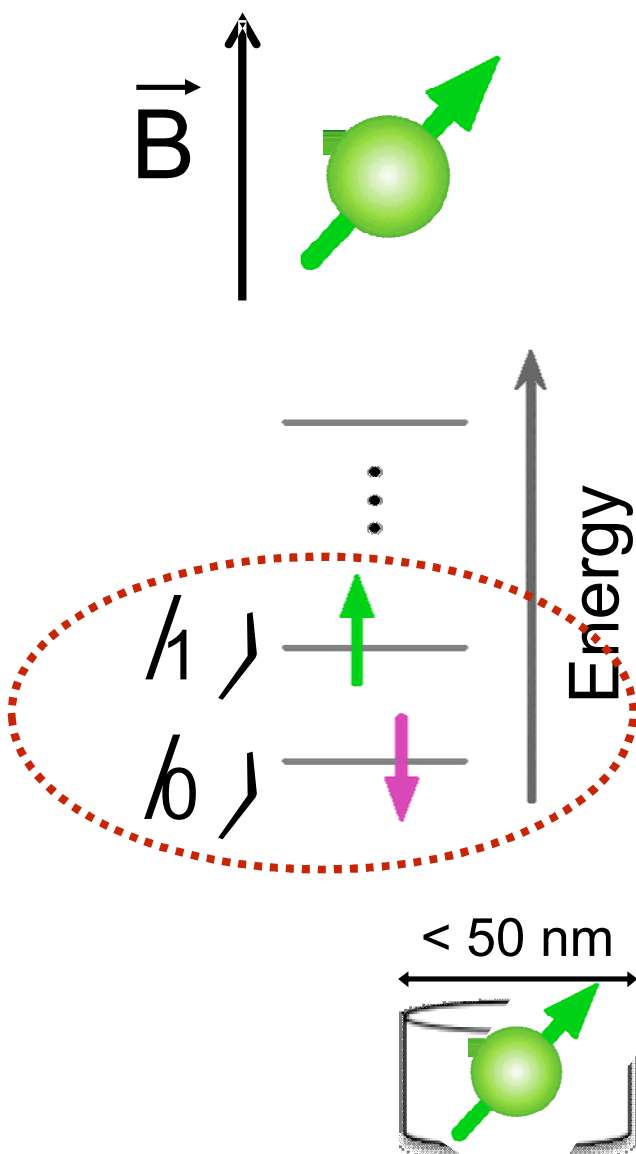


- A reliable Si QD platform
 - Well-isolated two-level system
 - Dot-reservoir tunnel barrier tunability
 - Extensible fabrication
- Our approach
 - Split accumulation gate architecture
 - Prototypes and fabrication process
- Results
 - Single electron regime
 - Dot-reservoir tunnel rate control
 - Valley splitting tuning
- Conclusion

A reliable platform for scaling up QD arrays

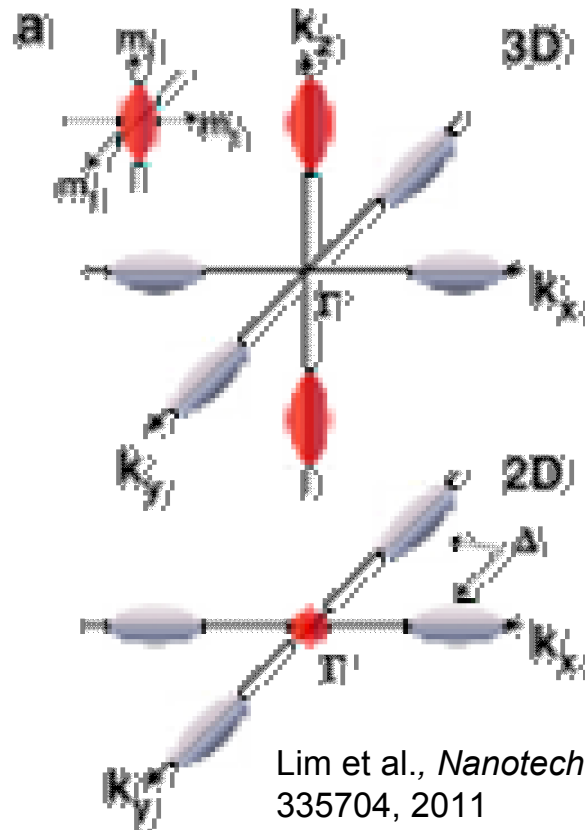


(1) Well-isolated two-level system



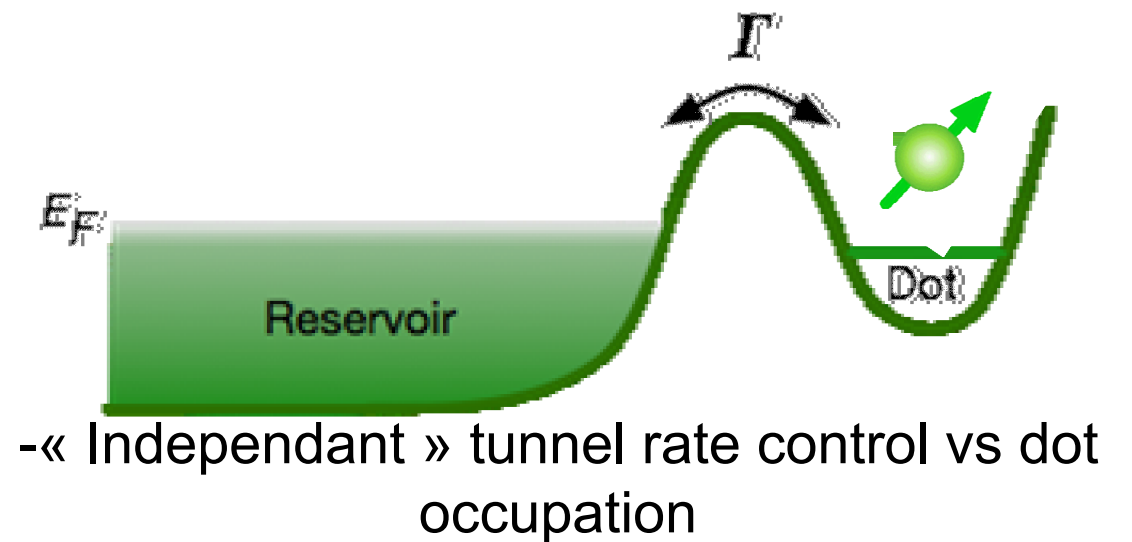
-Strong confinement

-Large and tunable valley splitting



Lim et al., *Nanotechnology* 22, 335704, 2011

(2) Dot-reservoir tunnel rate control



(3) Extensible fabrication



- CMOS compatibility

-Reproducibility and yield

-Simplified operation

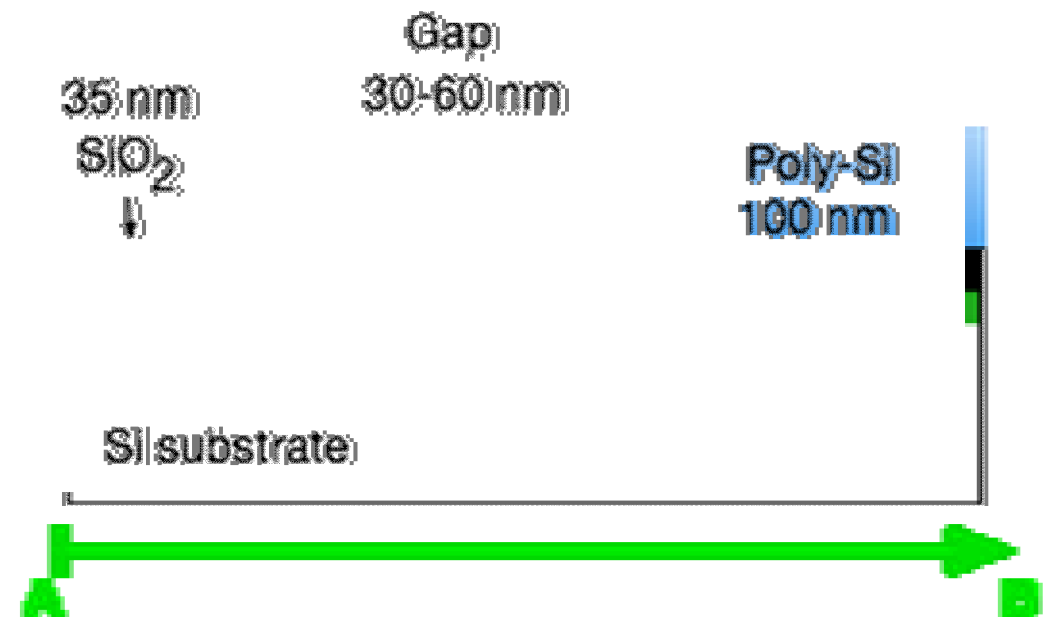
Our approach

Split accumulation gate architecture

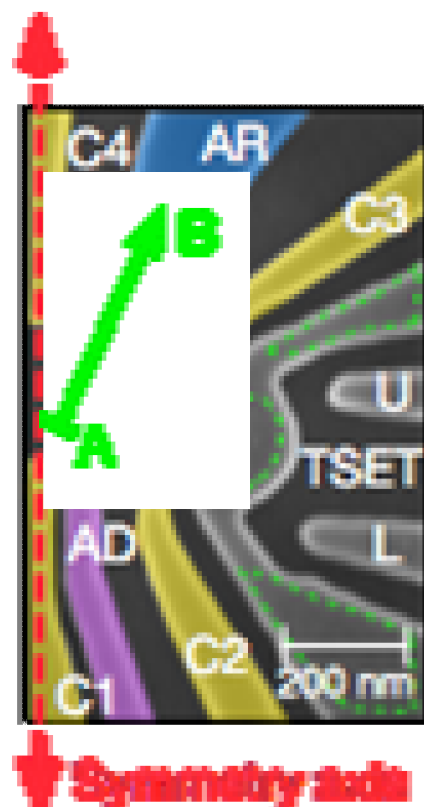
- Poly-silicon gates: CMOS compatible, less stress and noise than Al gates.
- Single gate stack subtractive fabrication process (no lift-off), CMOS compatible and better yield.

Sandia National Laboratories fabrication process

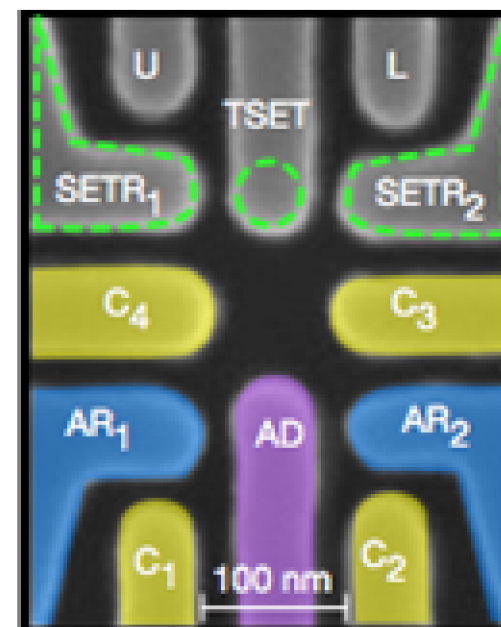
- Minimalist planar architecture: we have to make it work with one less gate.
- Fabrication: check. Do we fulfill the other criterias?



Single-lead



Double-lead device



Tested in



UNIVERSITÉ DE
SHERBROOKE

$T_e = 125$ mK

Charge detection
only

Tested in



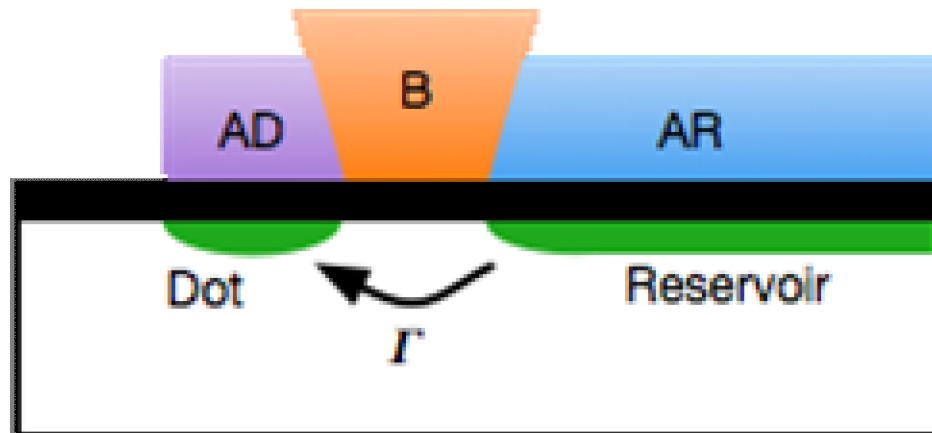
Sandia
National
Laboratories

$T_e = 160$ mK

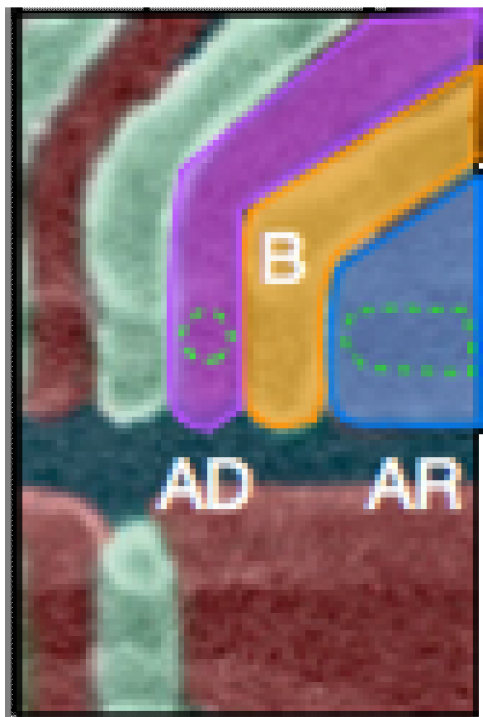
Charge detection +
transport

Dot-reservoir tunnel barrier control methods

Local accumulation devices

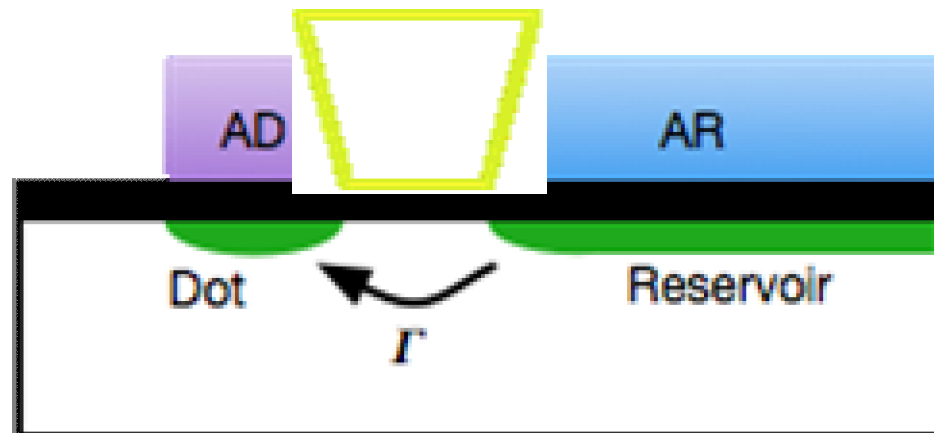


Dedicated barrier gate

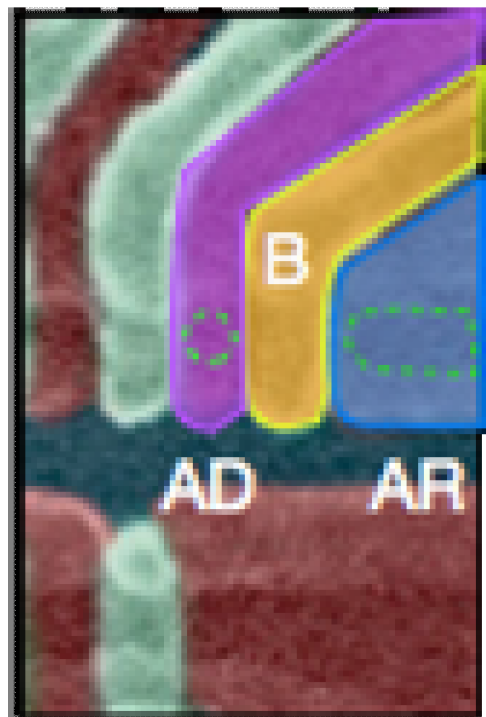


Dot-reservoir tunnel barrier control methods

Local accumulation devices

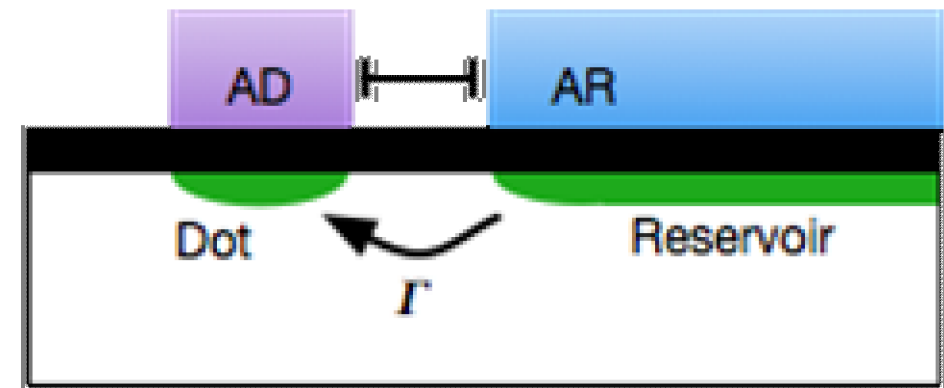
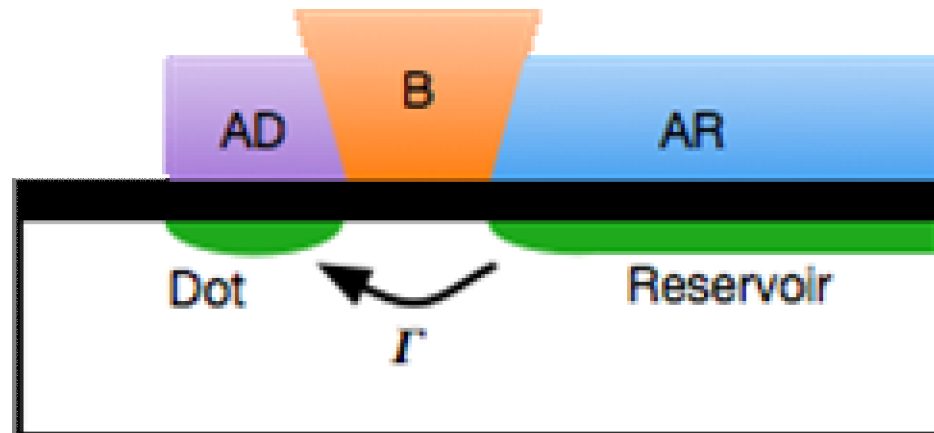


Dedicated barrier gate

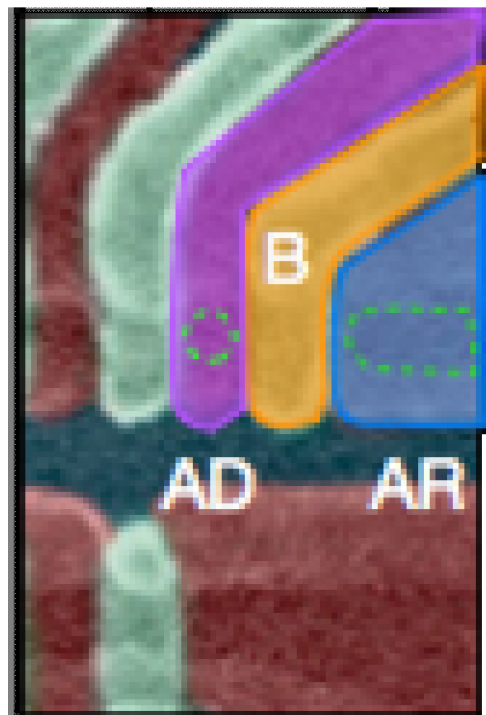


Dot-reservoir tunnel barrier control methods

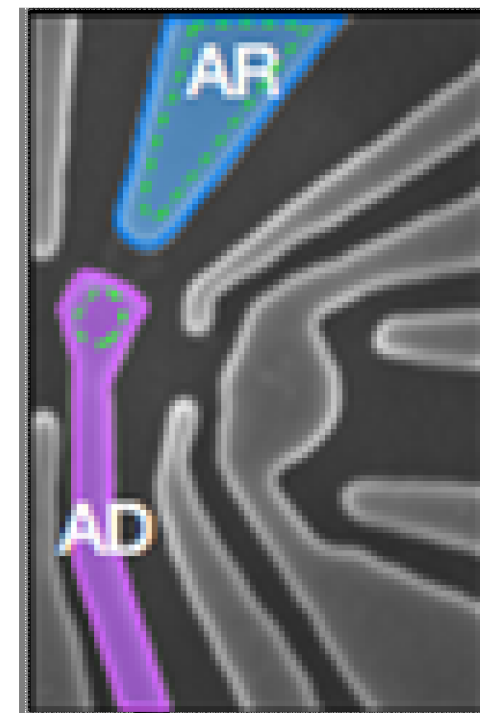
Local accumulation devices



Dedicated barrier gate

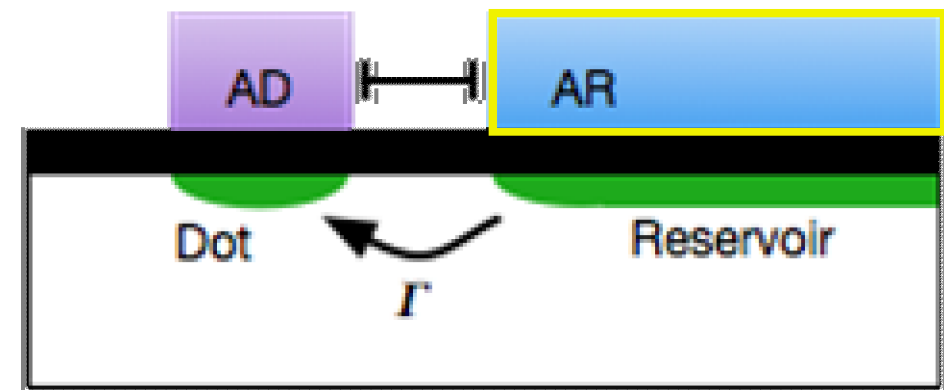
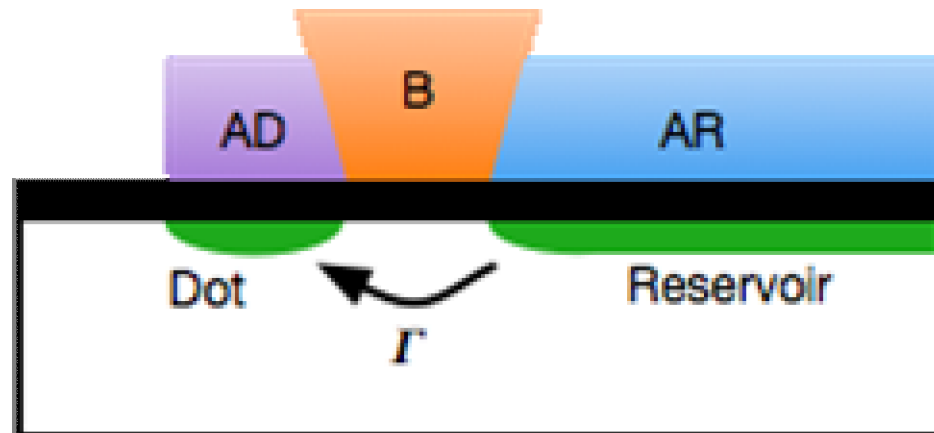


Minimalist architecture

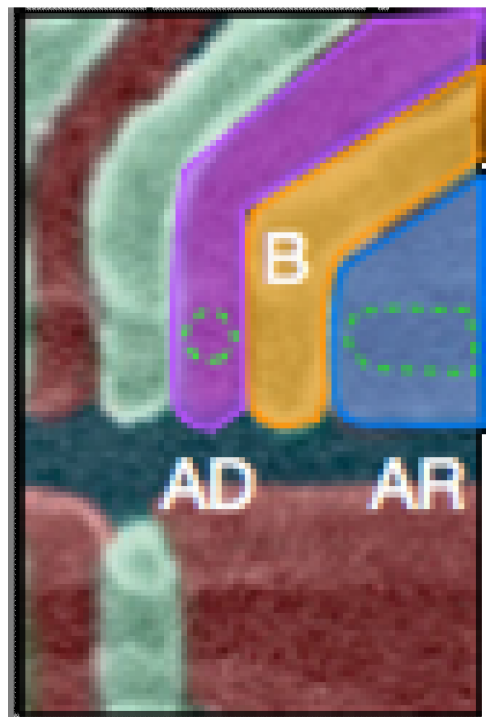


Dot-reservoir tunnel barrier control methods

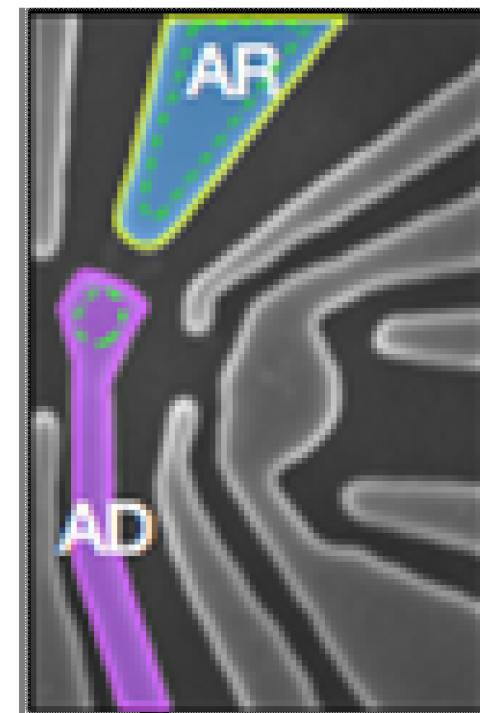
Local accumulation devices



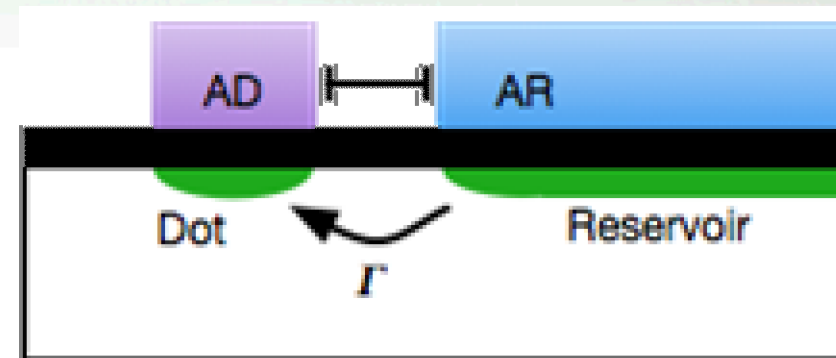
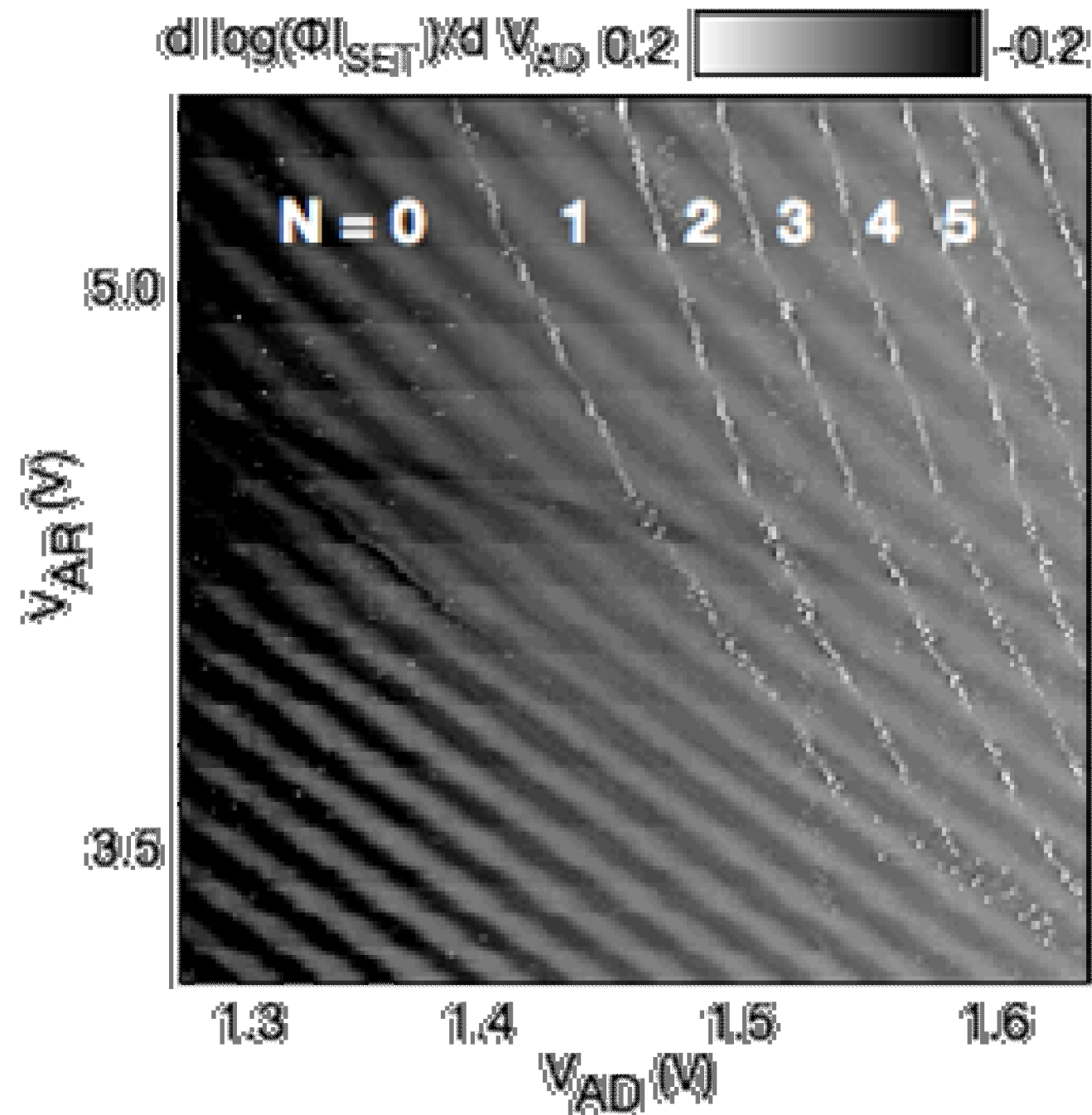
Dedicated barrier gate



Minimalist architecture



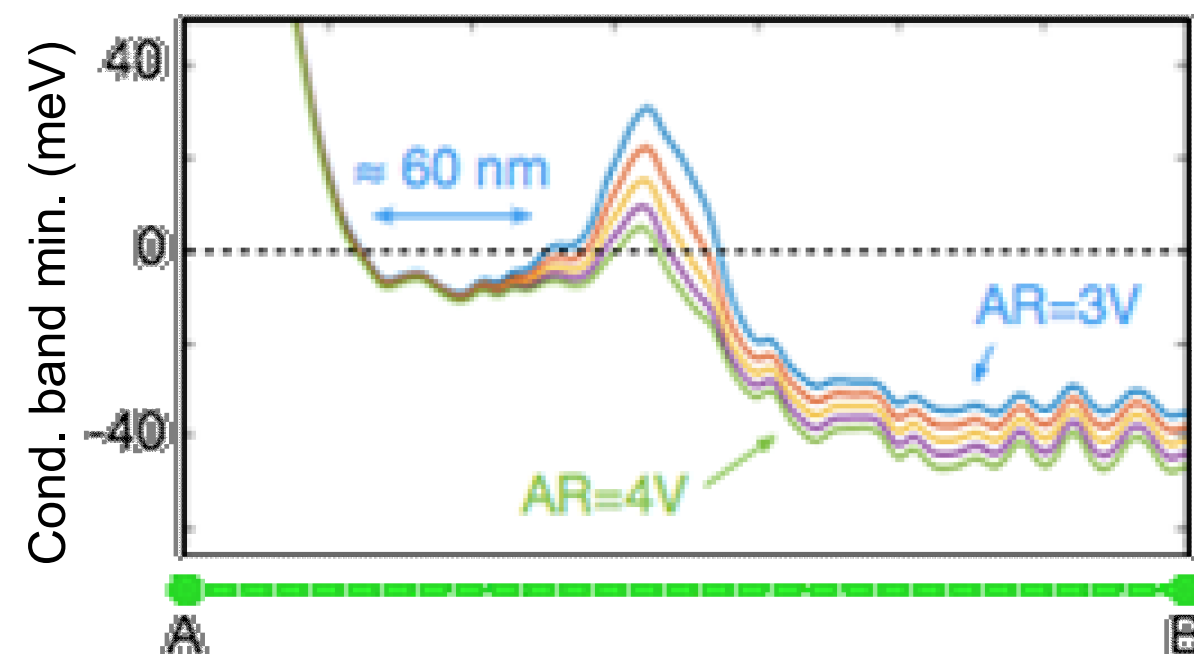
Single-electron regime



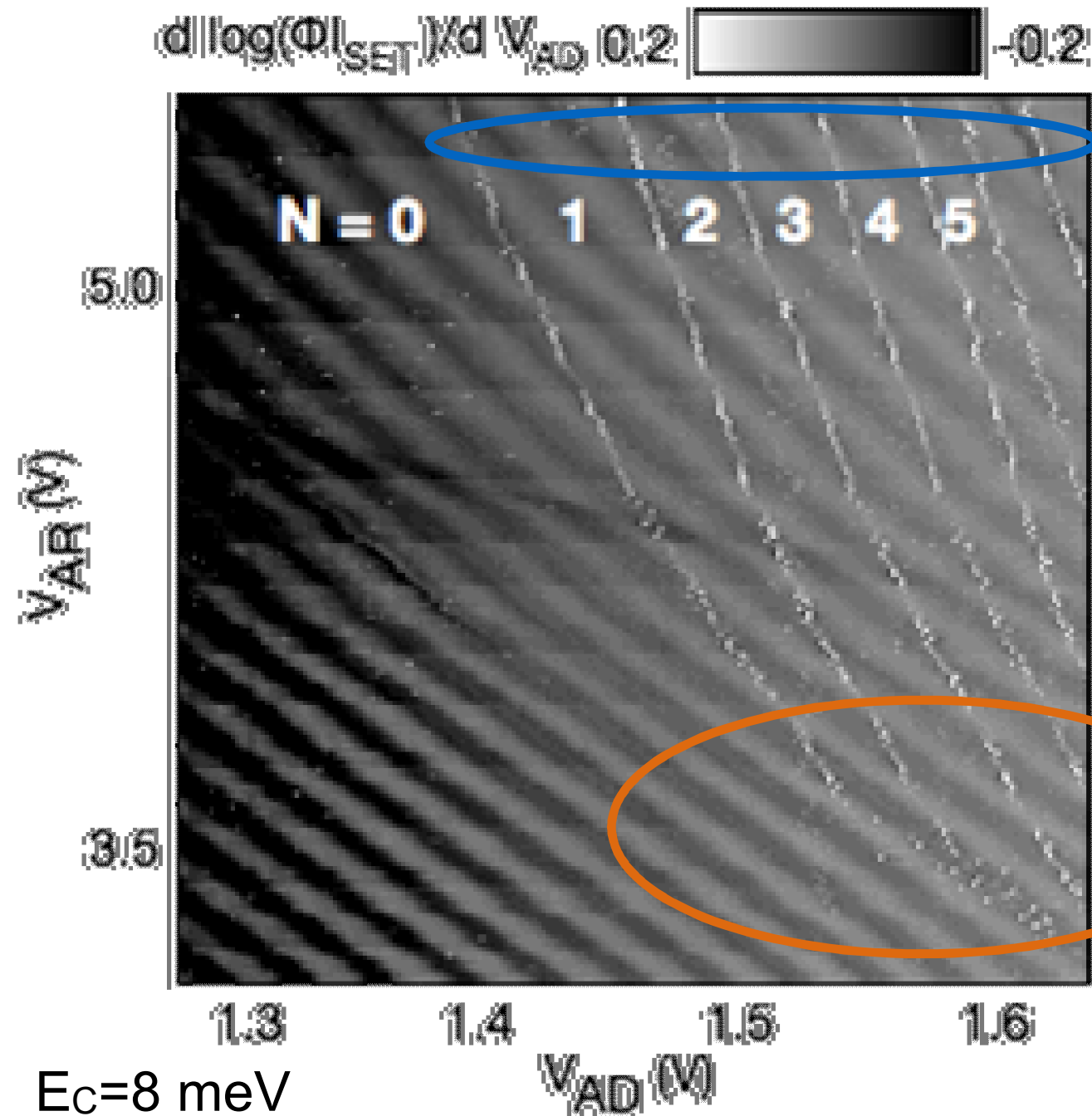
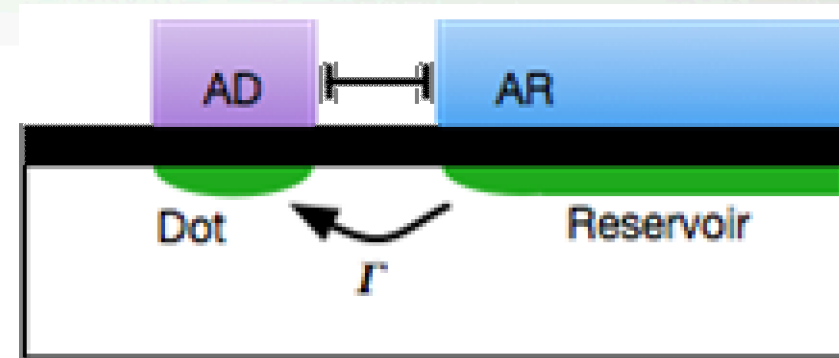
Single lead device

Background:
SET oscillations

Effect of AR on
the tunnel rate Γ



Single-electron regime

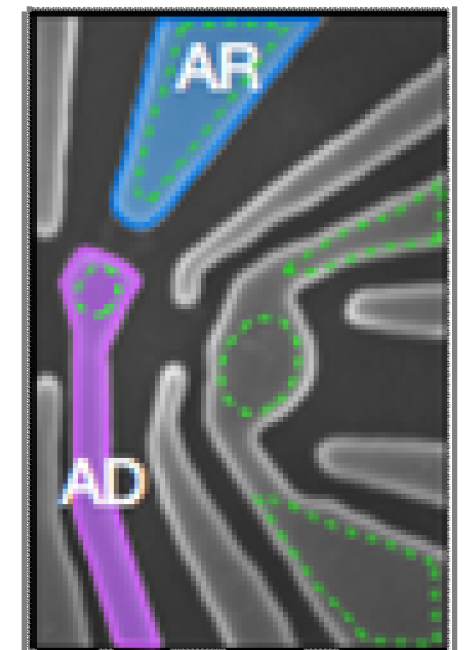


Fast Γ compared to measurement time

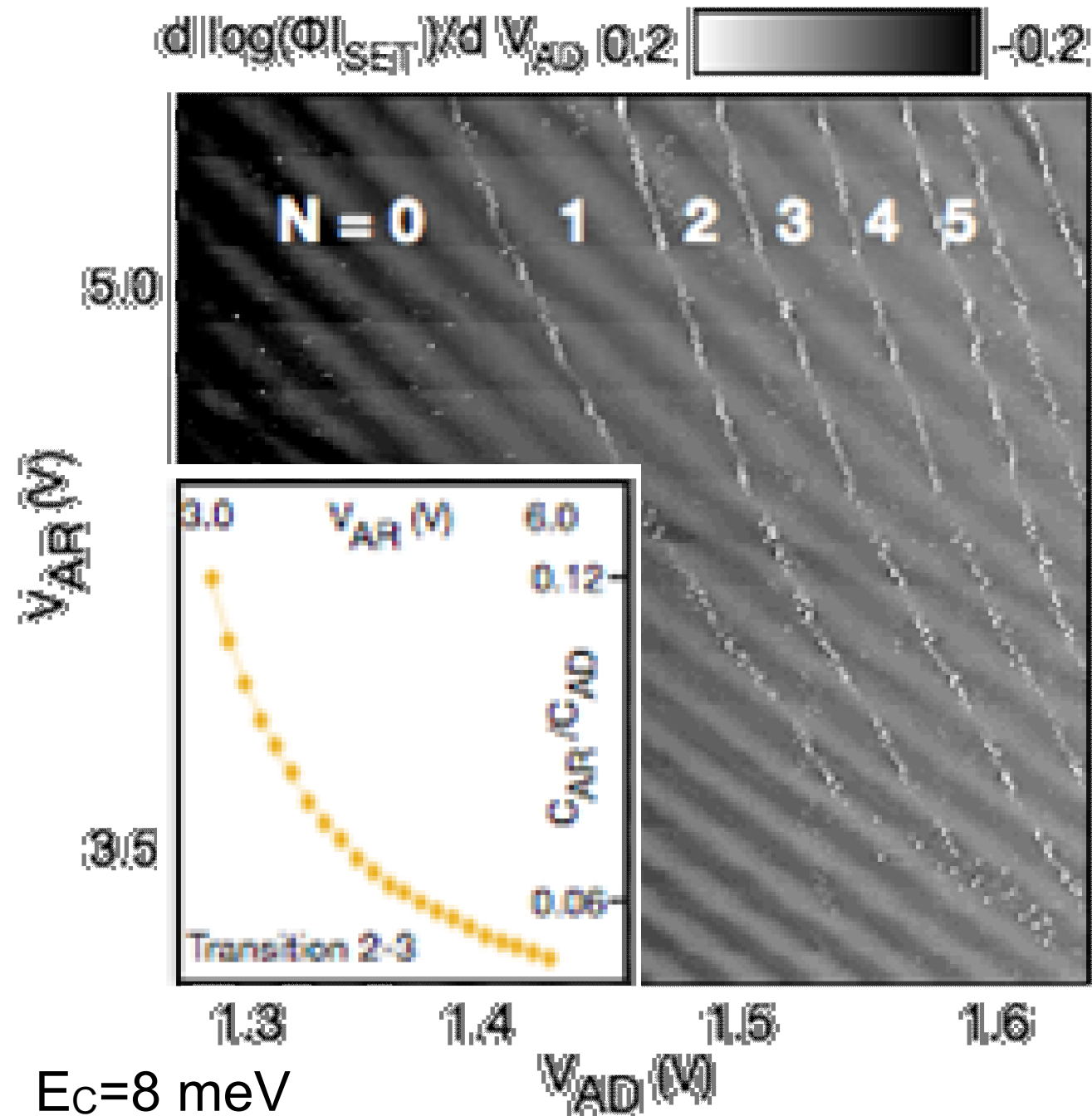
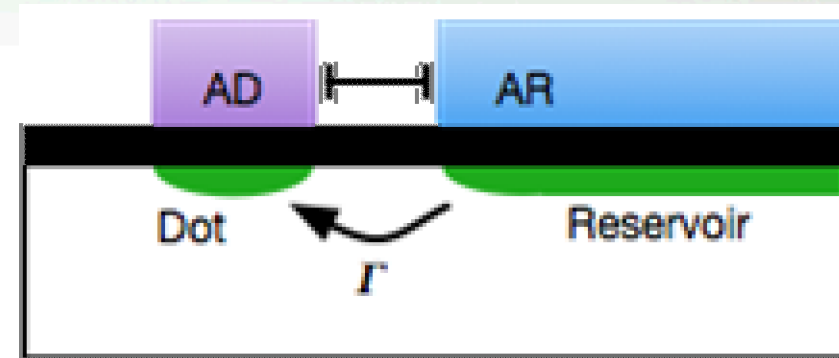
Effect of AR on the tunnel rate Γ

Slow Γ compared to measurement time

Single-lead device



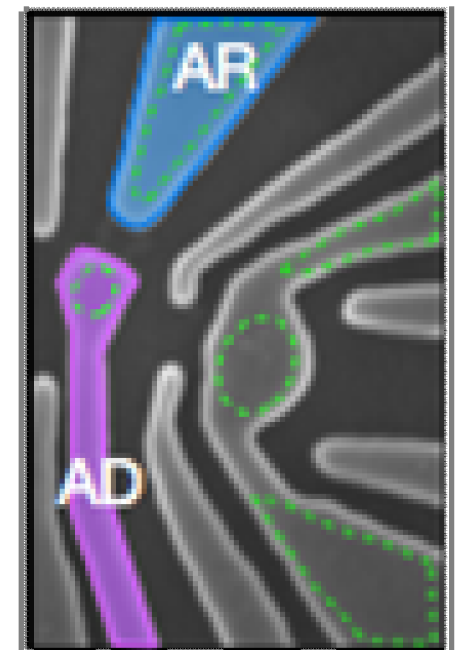
Single-electron regime



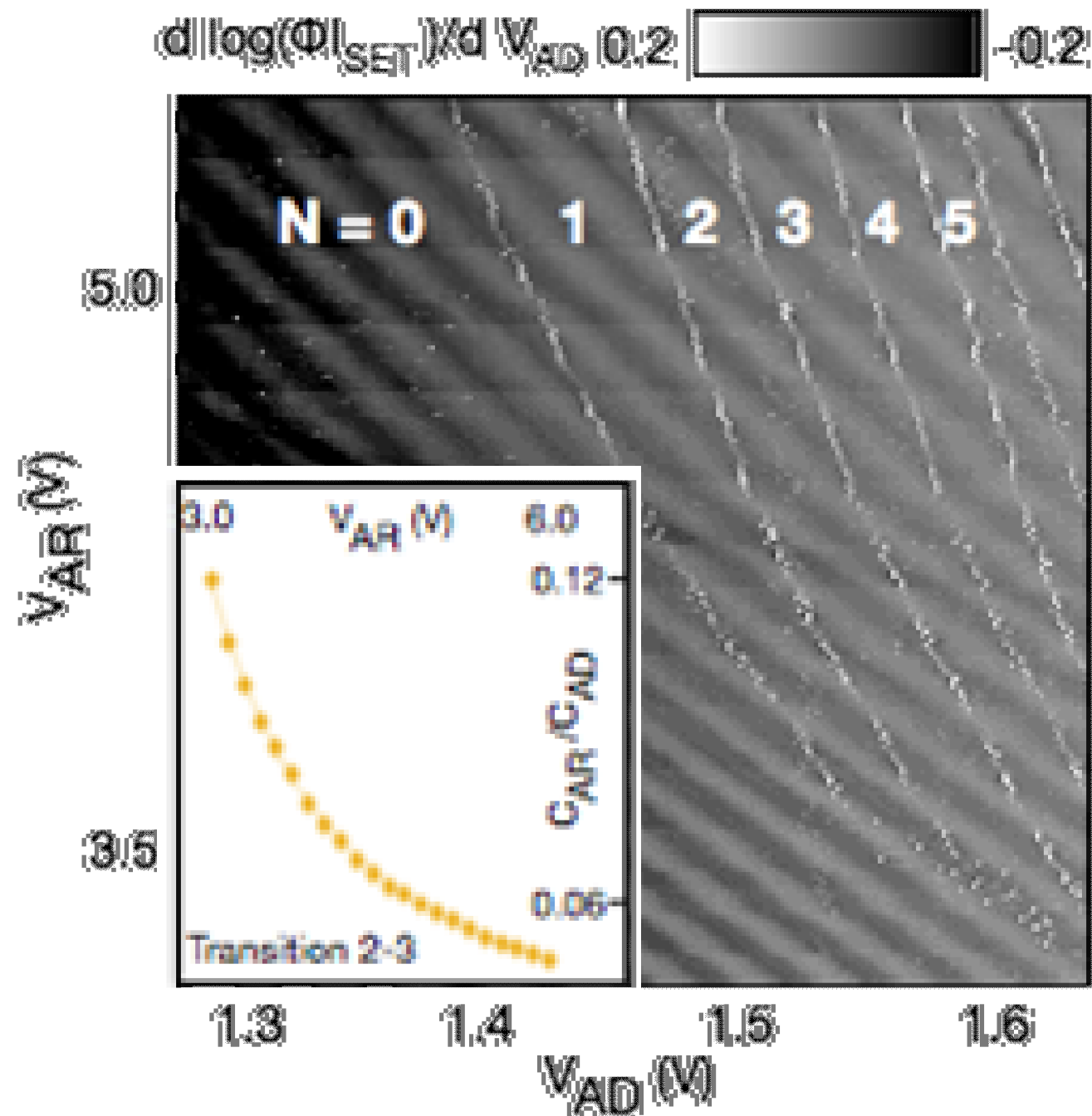
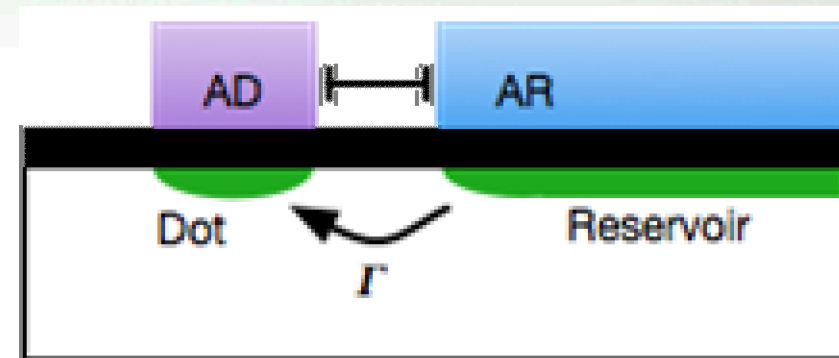
Gradual decrease of $C_{\text{AR-dot}}/C_{\text{AD-dot}}$

Filling of the reservoir

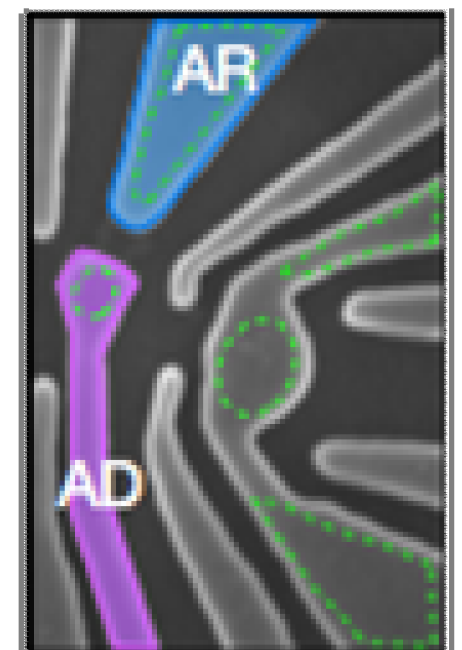
Single-lead device



Single-electron regime

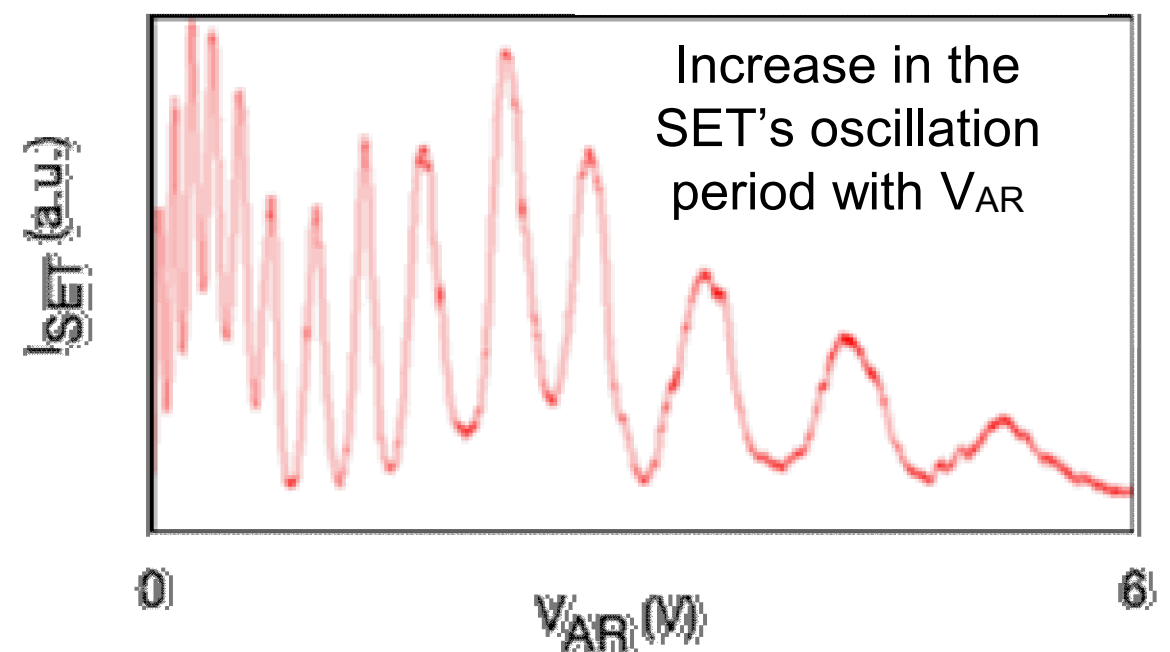


Single-lead device

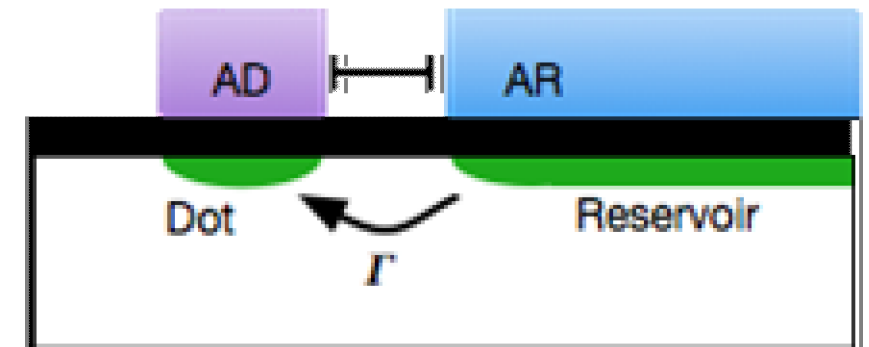
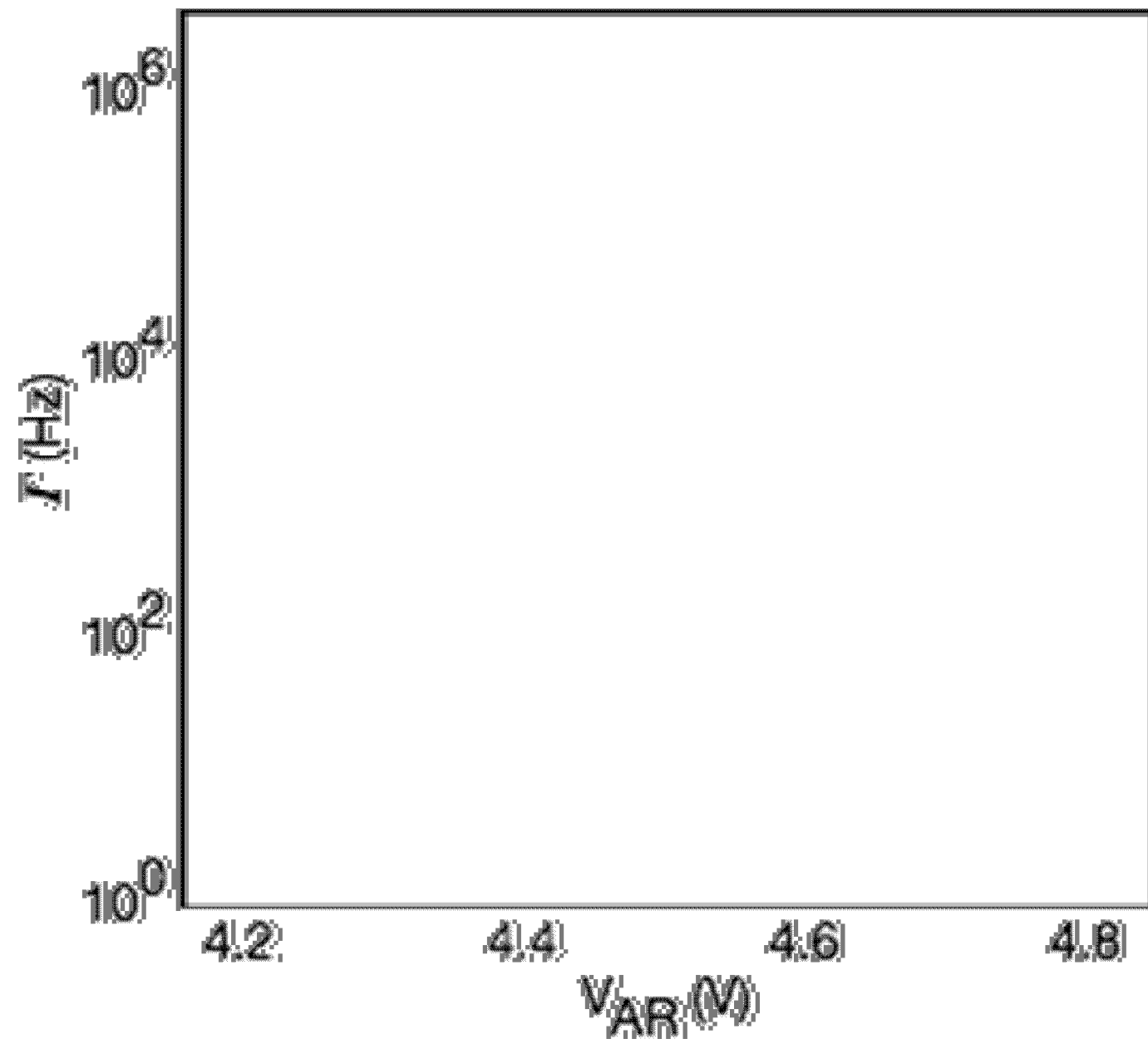


Gradual decrease of C_{AR-dot}/C_{AD-dot}

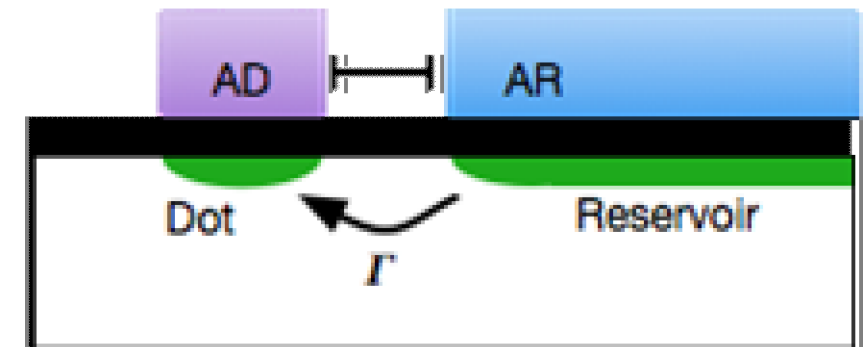
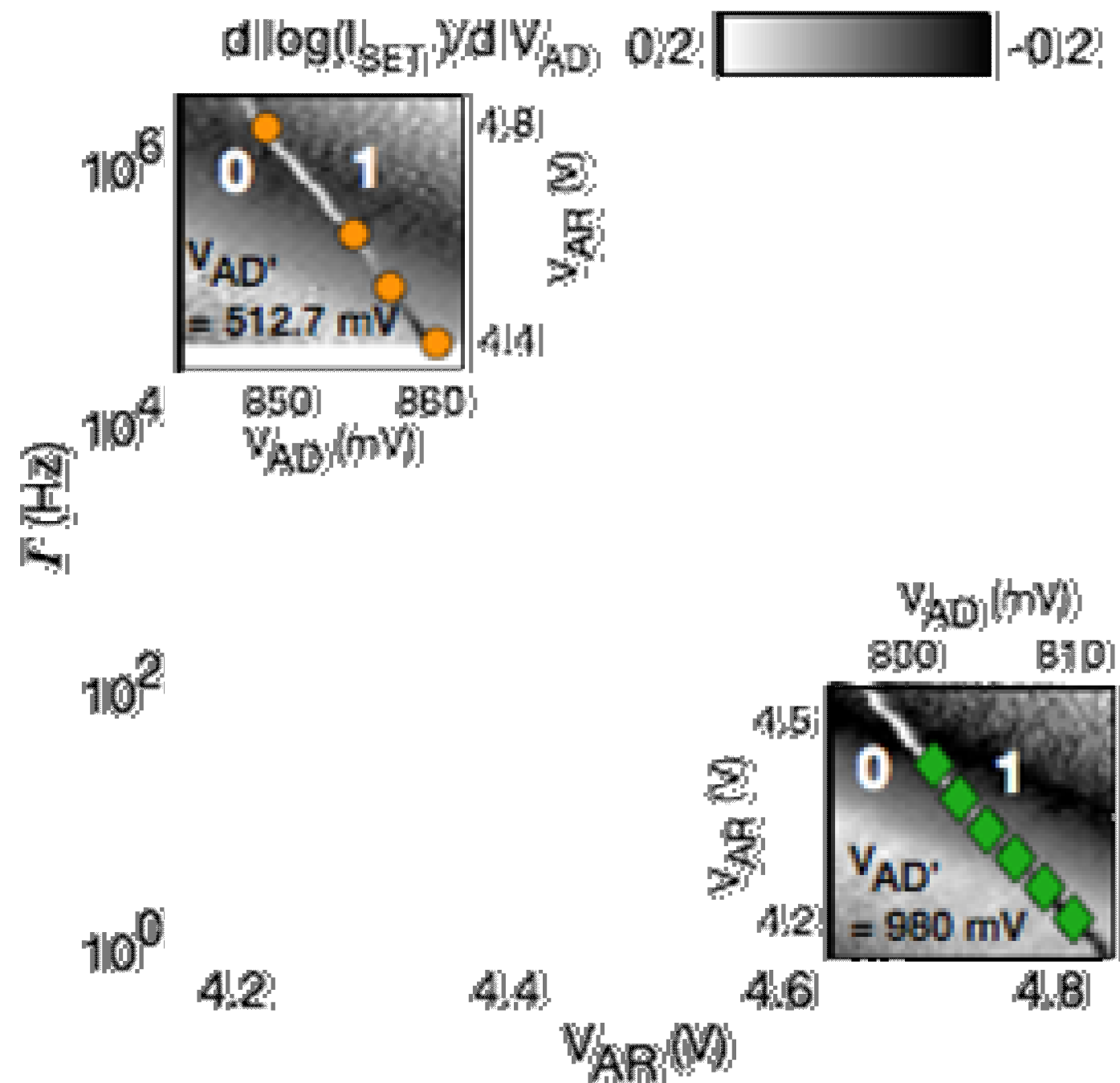
Filling of the reservoir



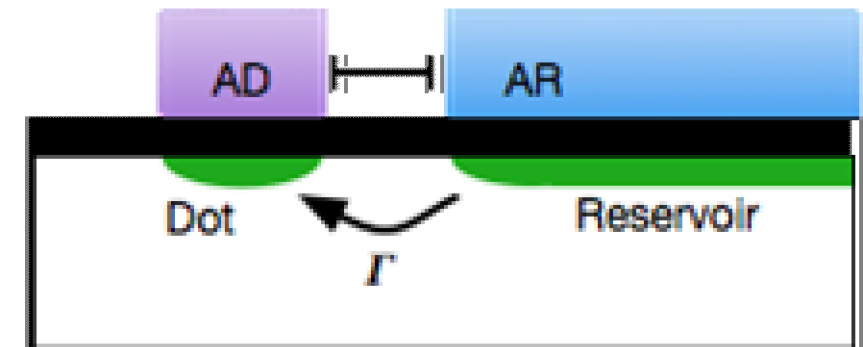
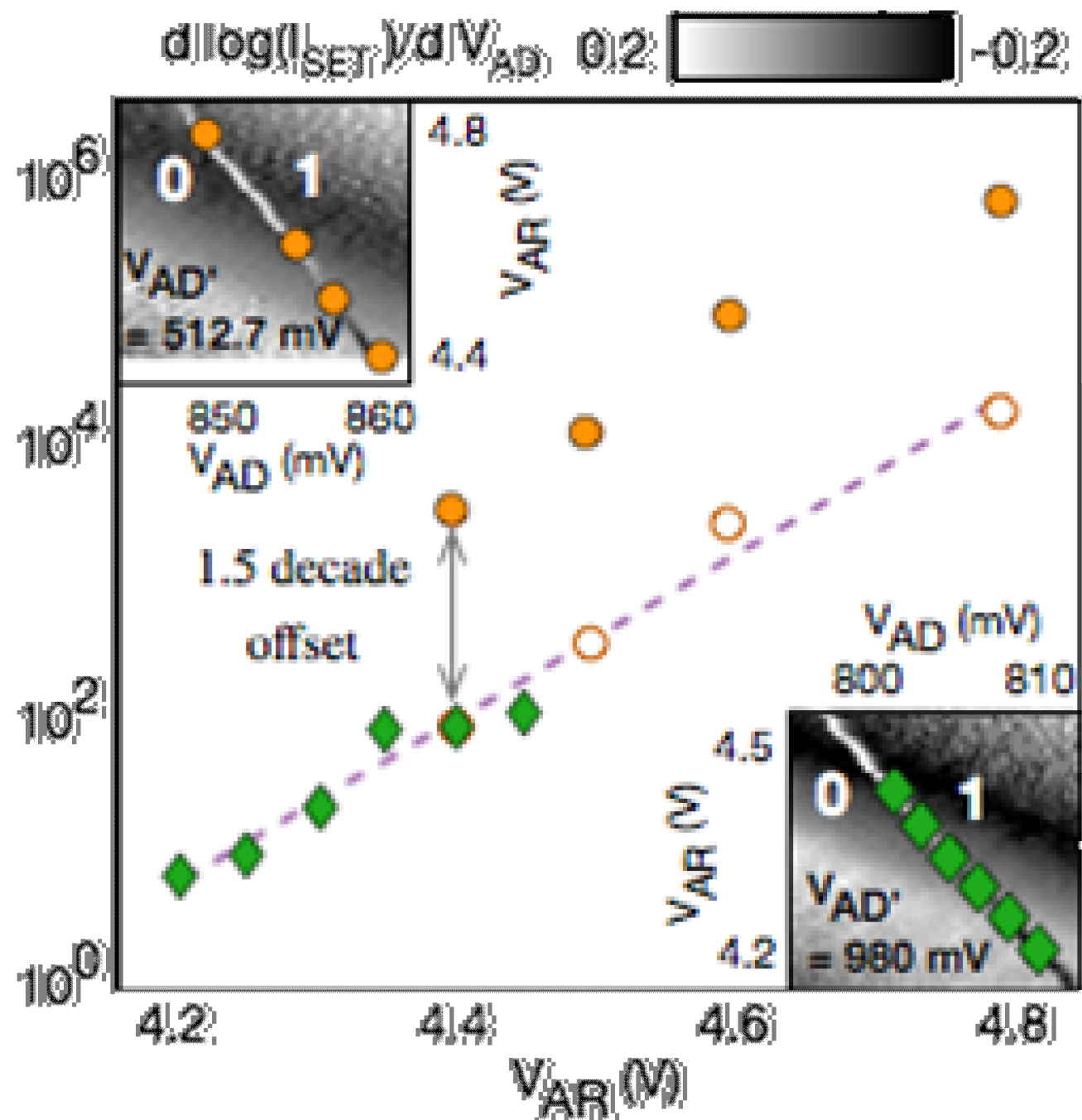
Tuning orthogonality: tunnel rate and dot occupation



Tuning orthogonality: tunnel rate and dot occupation



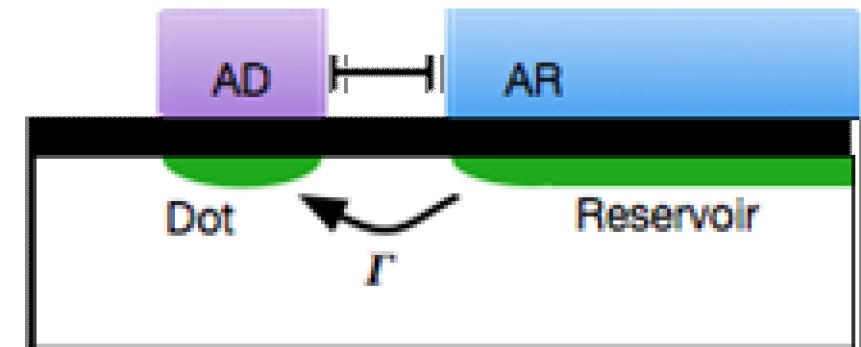
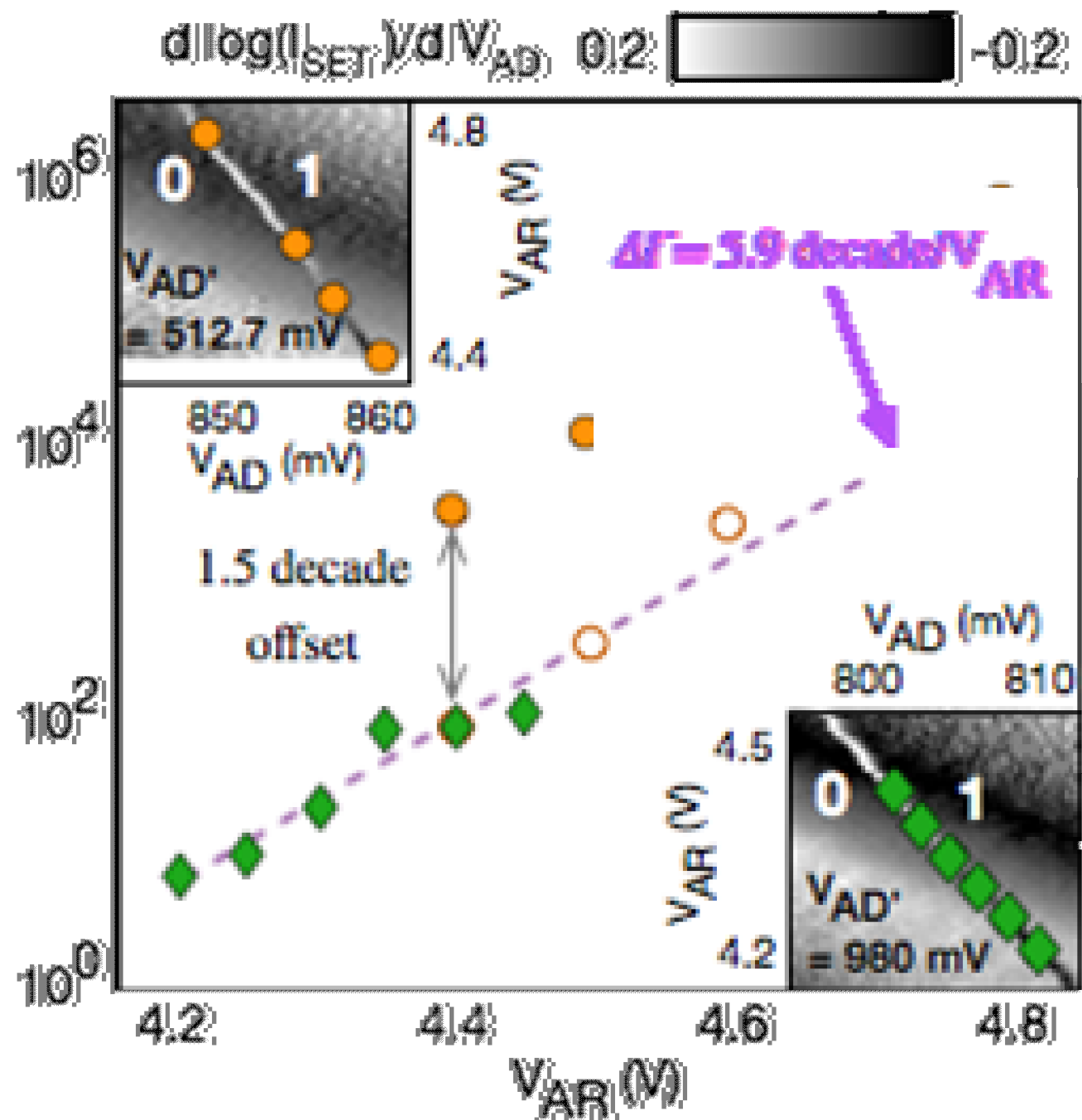
Tuning orthogonality: tunnel rate and dot occupation



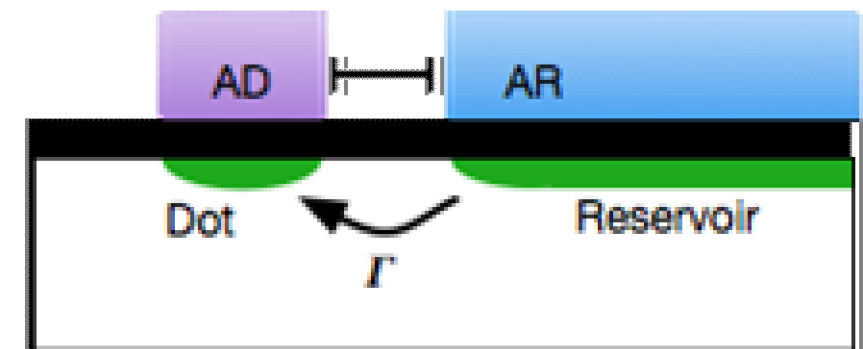
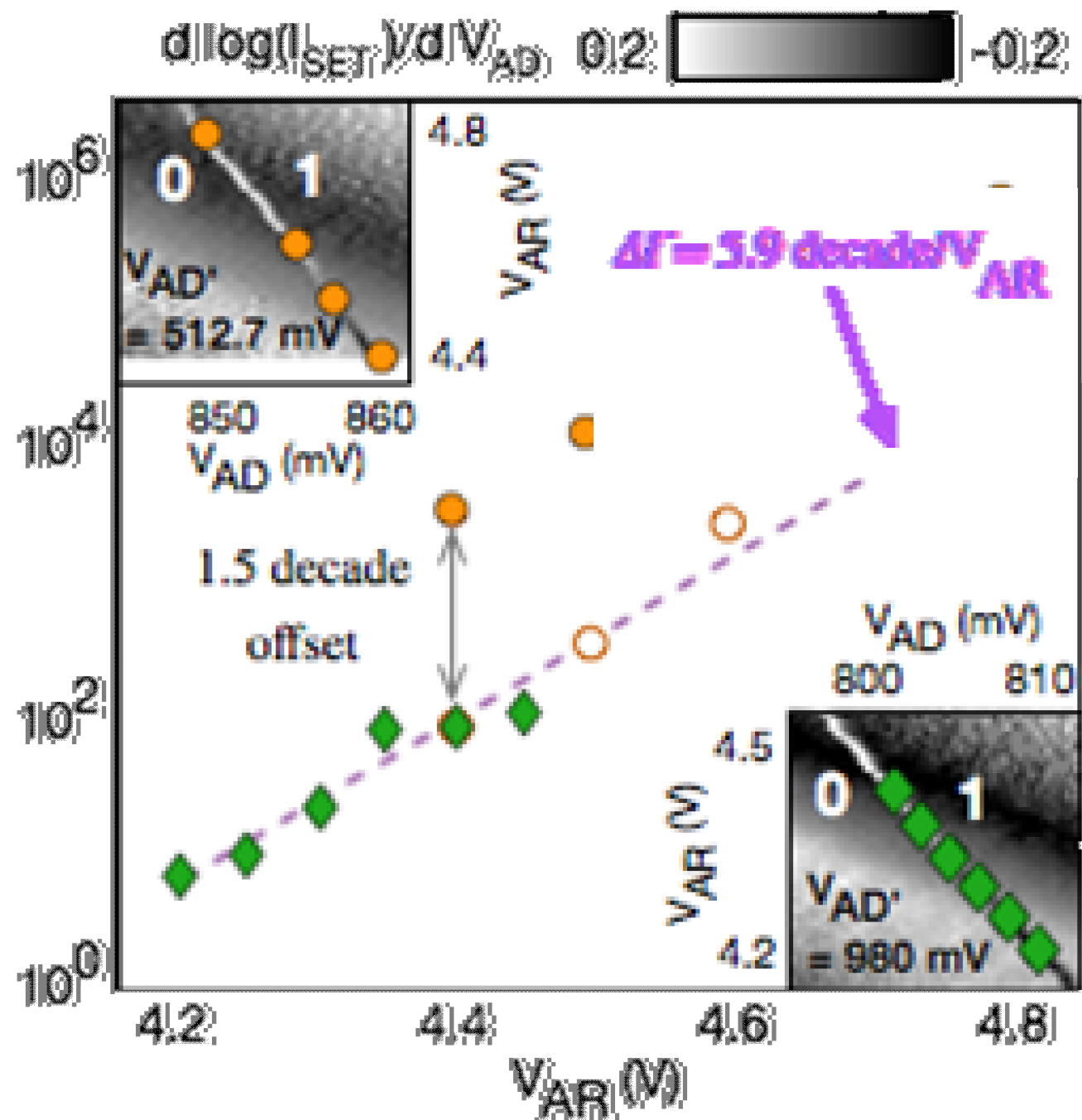
Gustavsson et al., Surf. Science Rep. 64, 191 (2009).

Elzerman et al., APL 84, 234617 (2004).

Tuning orthogonality: tunnel rate and dot occupation



Tuning orthogonality: tunnel rate and dot occupation



Tuning orthogonality

$$\beta_{AR, AD} = \Delta \Gamma_{AR} / \Delta \mu_{AR}$$

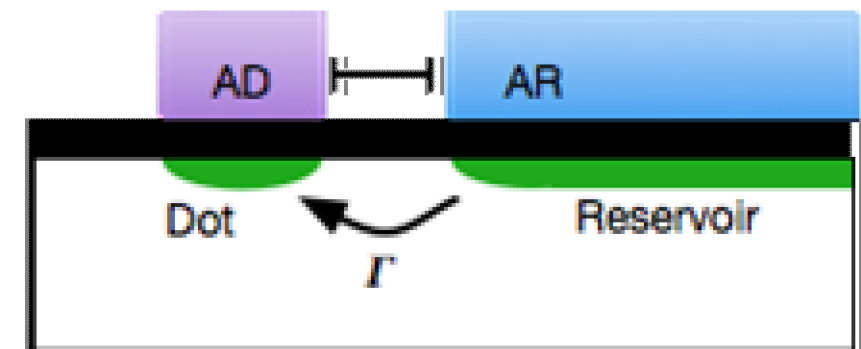
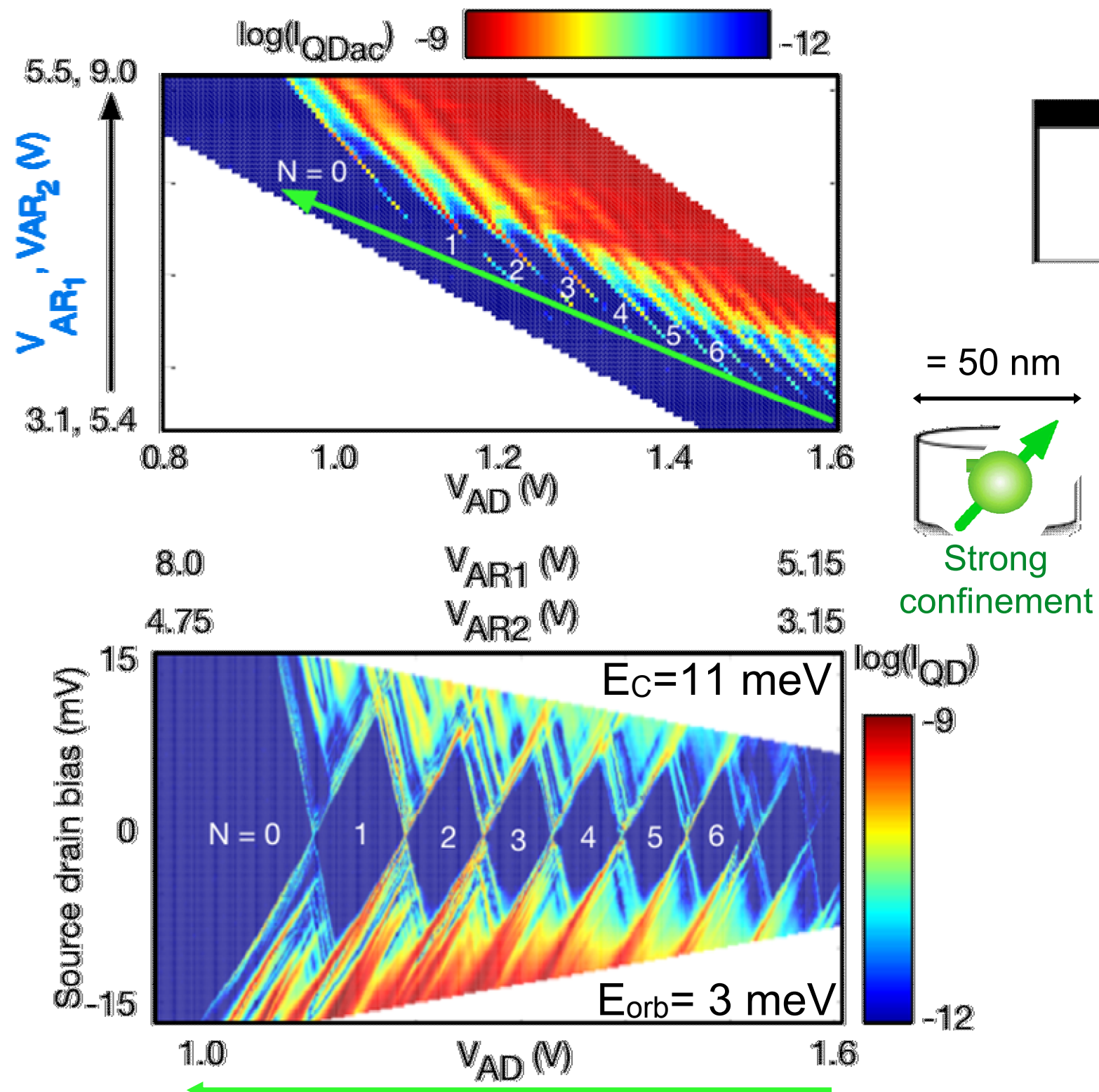
$$\beta_{AR, AD} \approx 0.9 \pm 0.3 \text{ decade/mV}$$

Dedicated barrier gate:

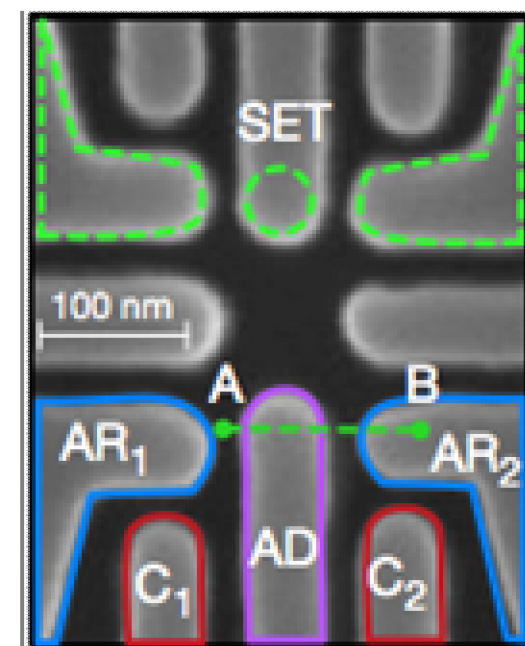
Zajac et al., APL 106, 223507 (2015).

$$\beta_{B, AD} \approx 1.1 \pm 0.3 \text{ decade/mV}$$

Quantum dot confinement in the split gate devices

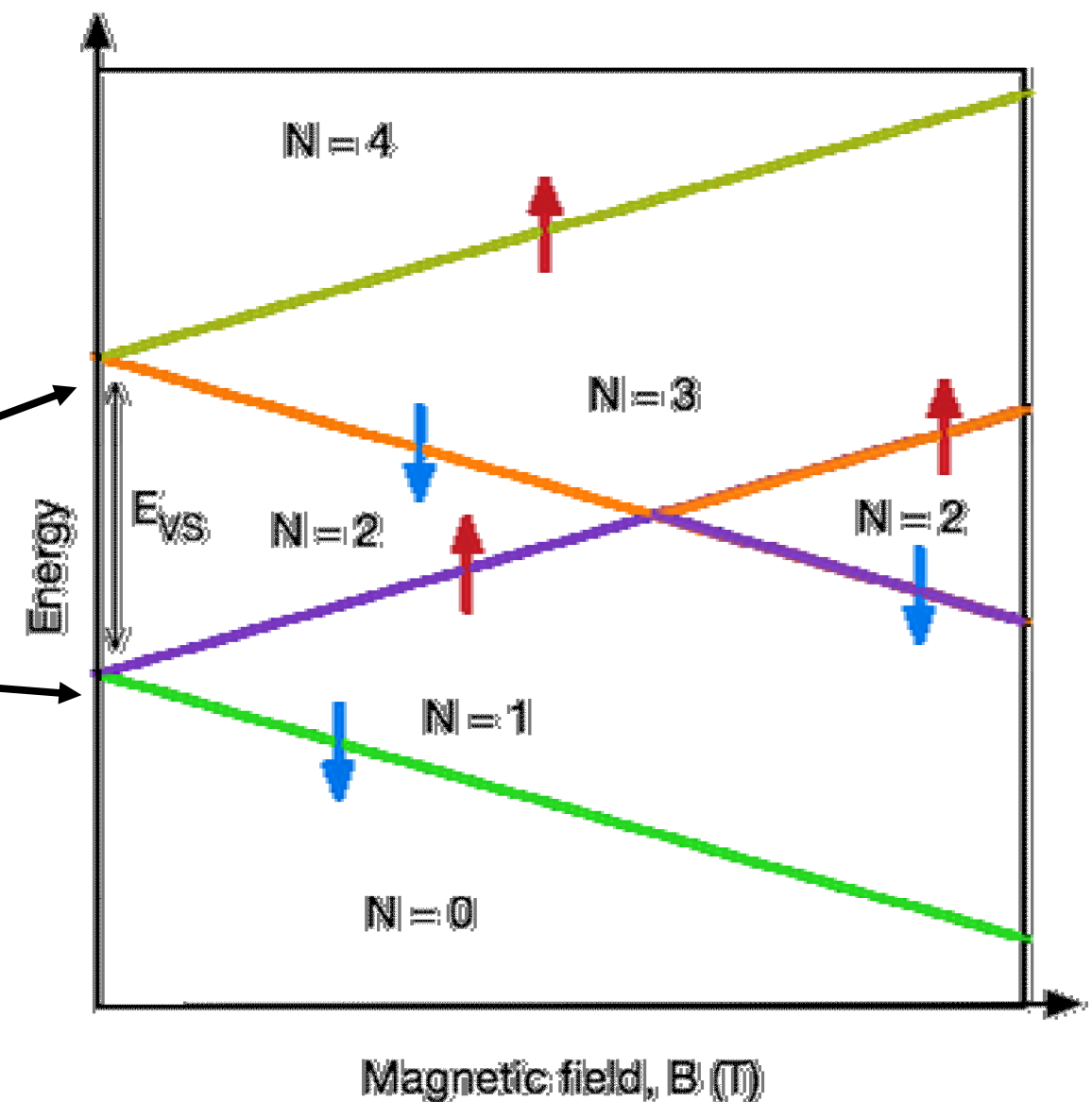
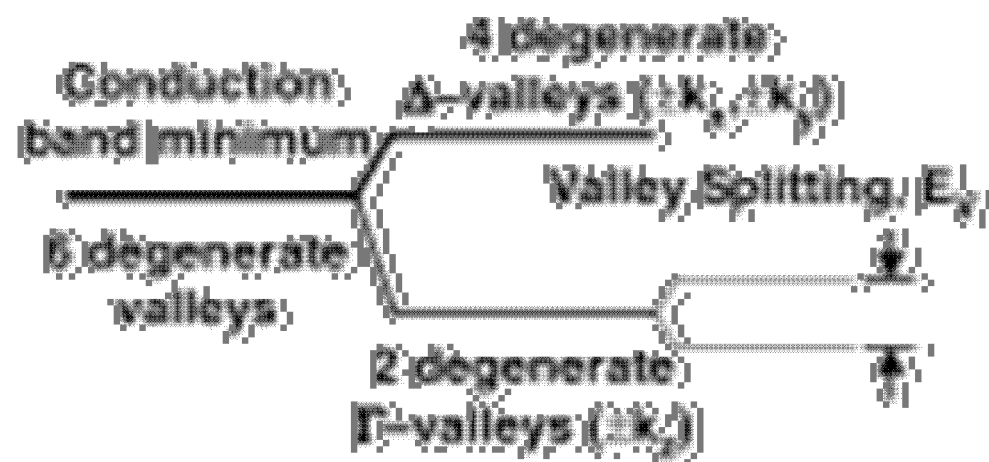


Double-lead device



Magnetospectroscopy: Spin states in silicon

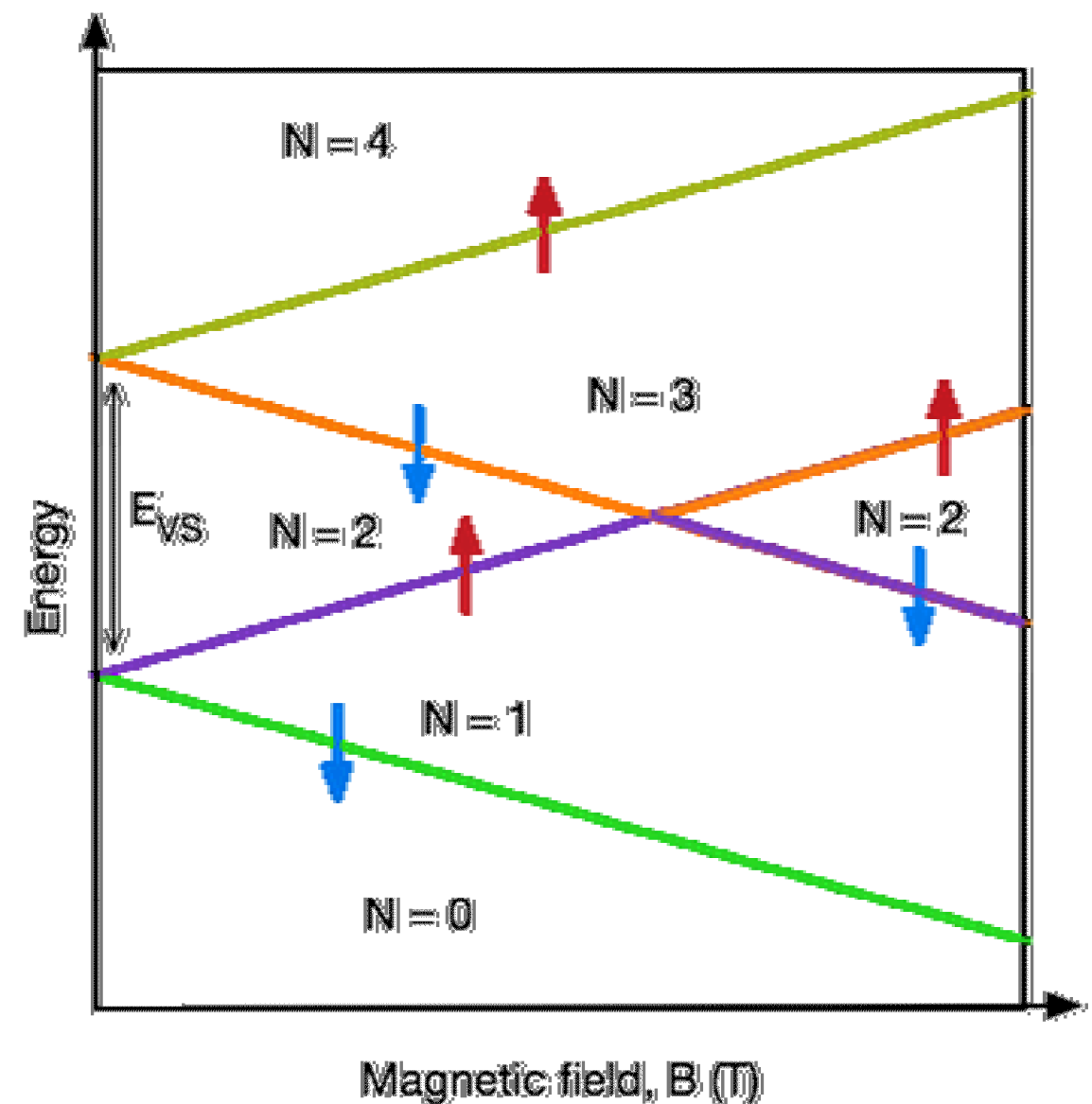
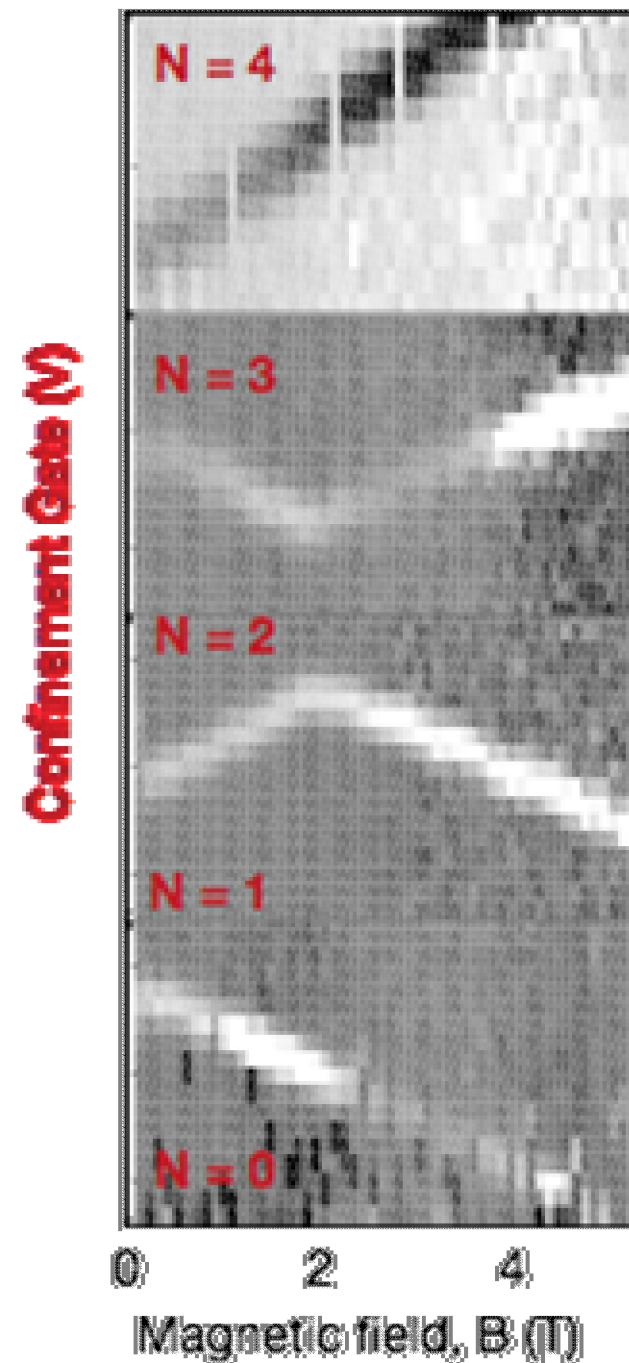
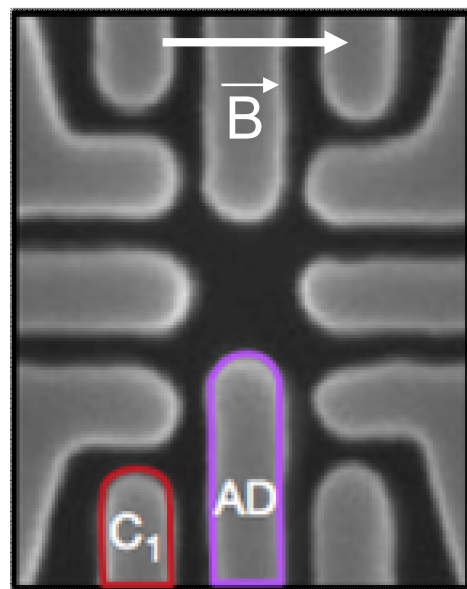
Valley degeneracy:



Electronic states in silicon quantum dots: Multivalley artificial atoms,
Y. Hada and M.Eto, PRB 68, 155322, 2003

Observation of the single electron regime in a highly tunable silicon quantum dot,
W. H. Lim et al, APL 95, 242102, 2009

Magnetospectroscopy: Spin states in silicon

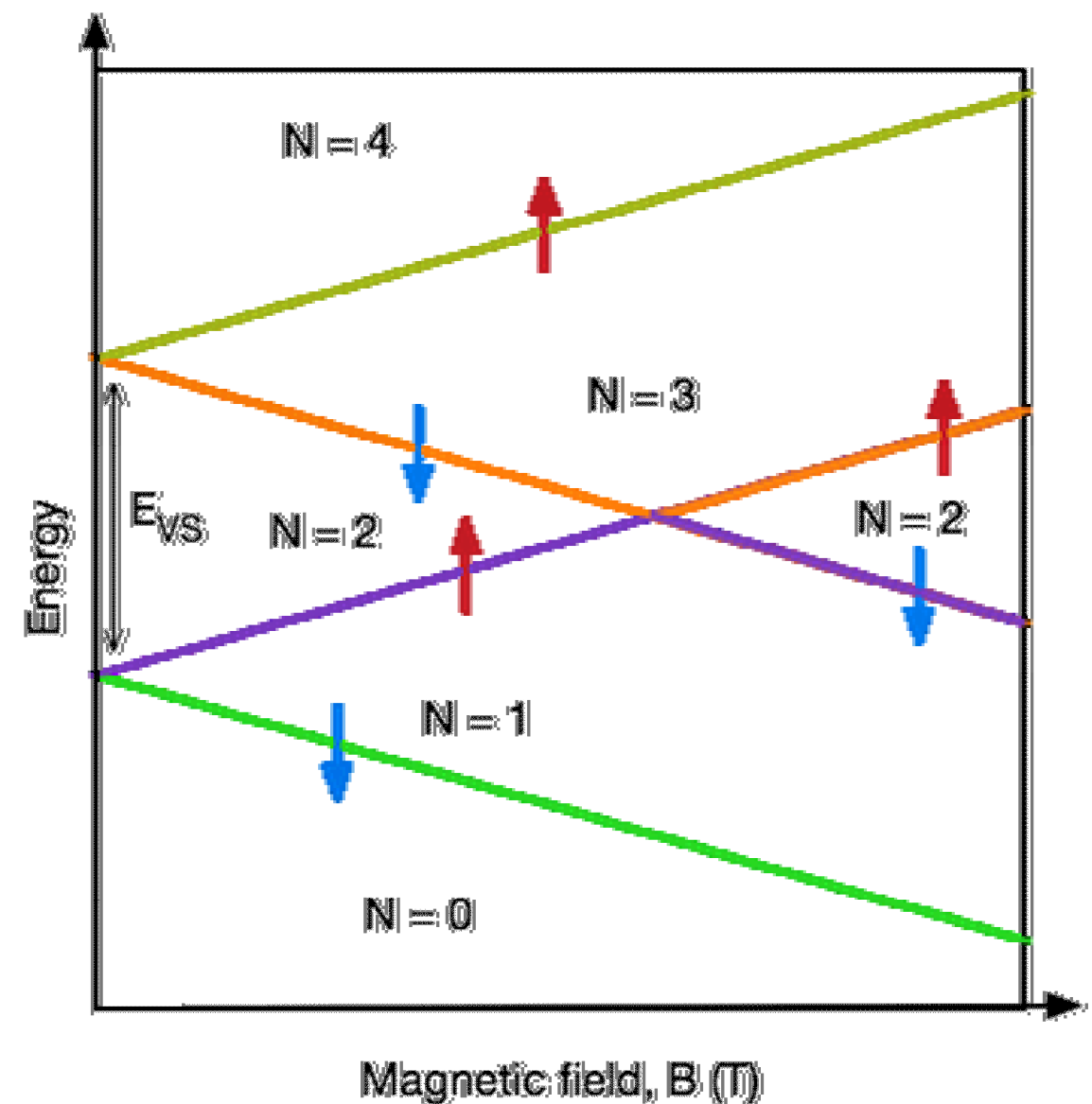
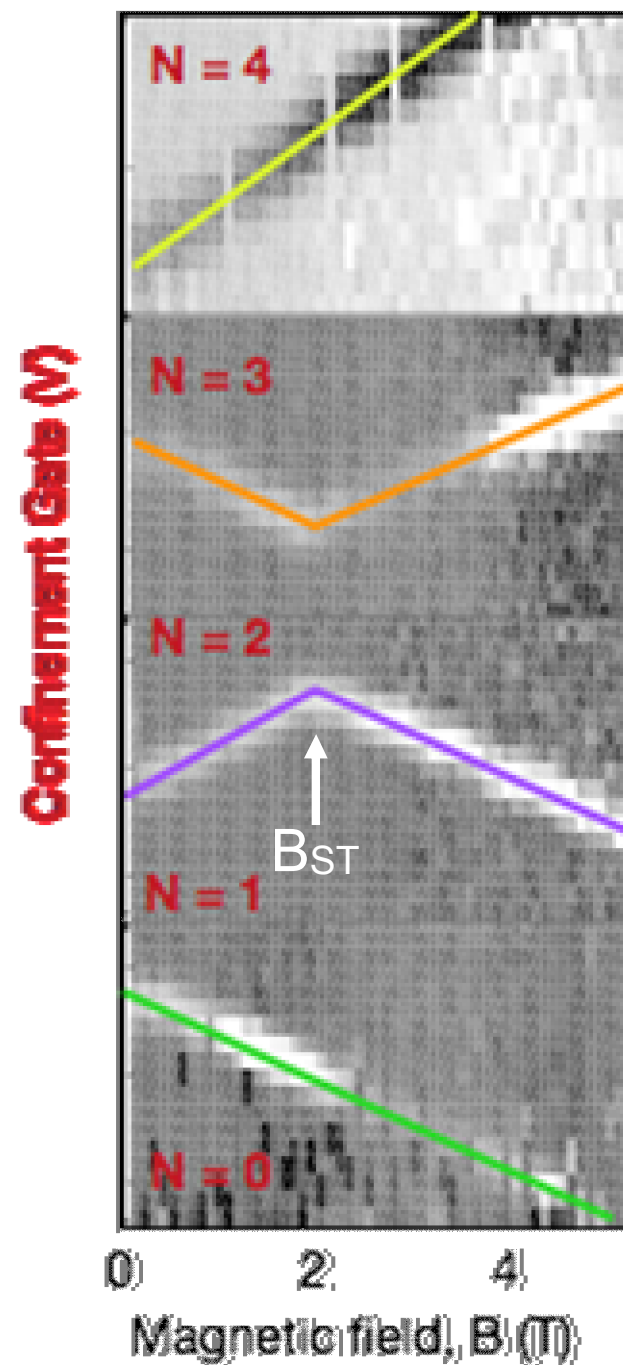
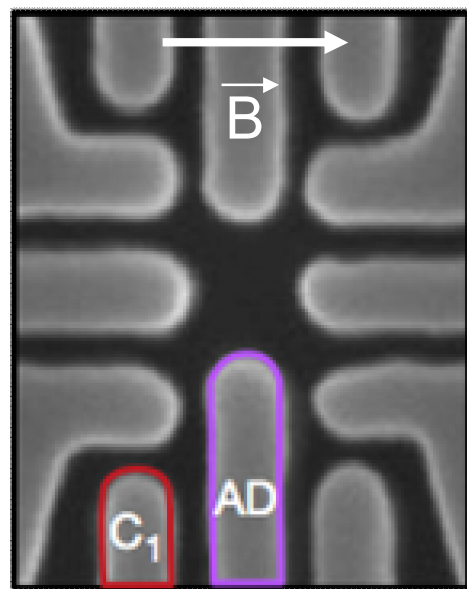


Electronic states in silicon quantum dots: Multivalley artificial atoms,
Y. Hada and M.Eto, PRB 68, 155322, 2003

Observation of the single electron regime in a highly tunable silicon quantum dot,
W. H. Lim et al, APL 95, 242102, 2009

Data by Martin Rudolph, SNL

Magnetospectroscopy: Spin states in silicon

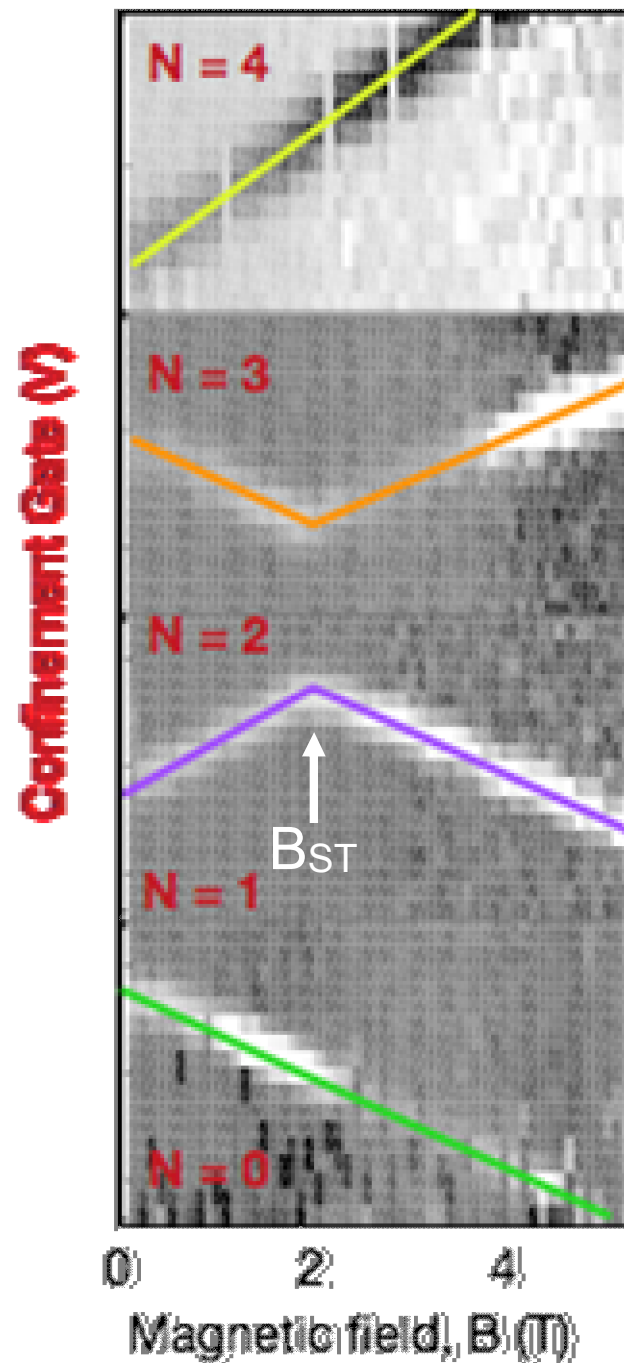
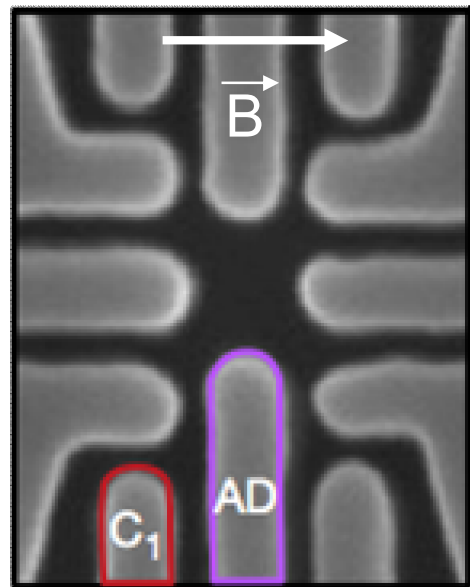


Electronic states in silicon quantum dots: Multivalley artificial atoms,
Y. Hada and M. Eto, PRB 68, 155322, 2003

Observation of the single electron regime in a highly tunable silicon quantum dot,
W. H. Lim et al, APL 95, 242102, 2009

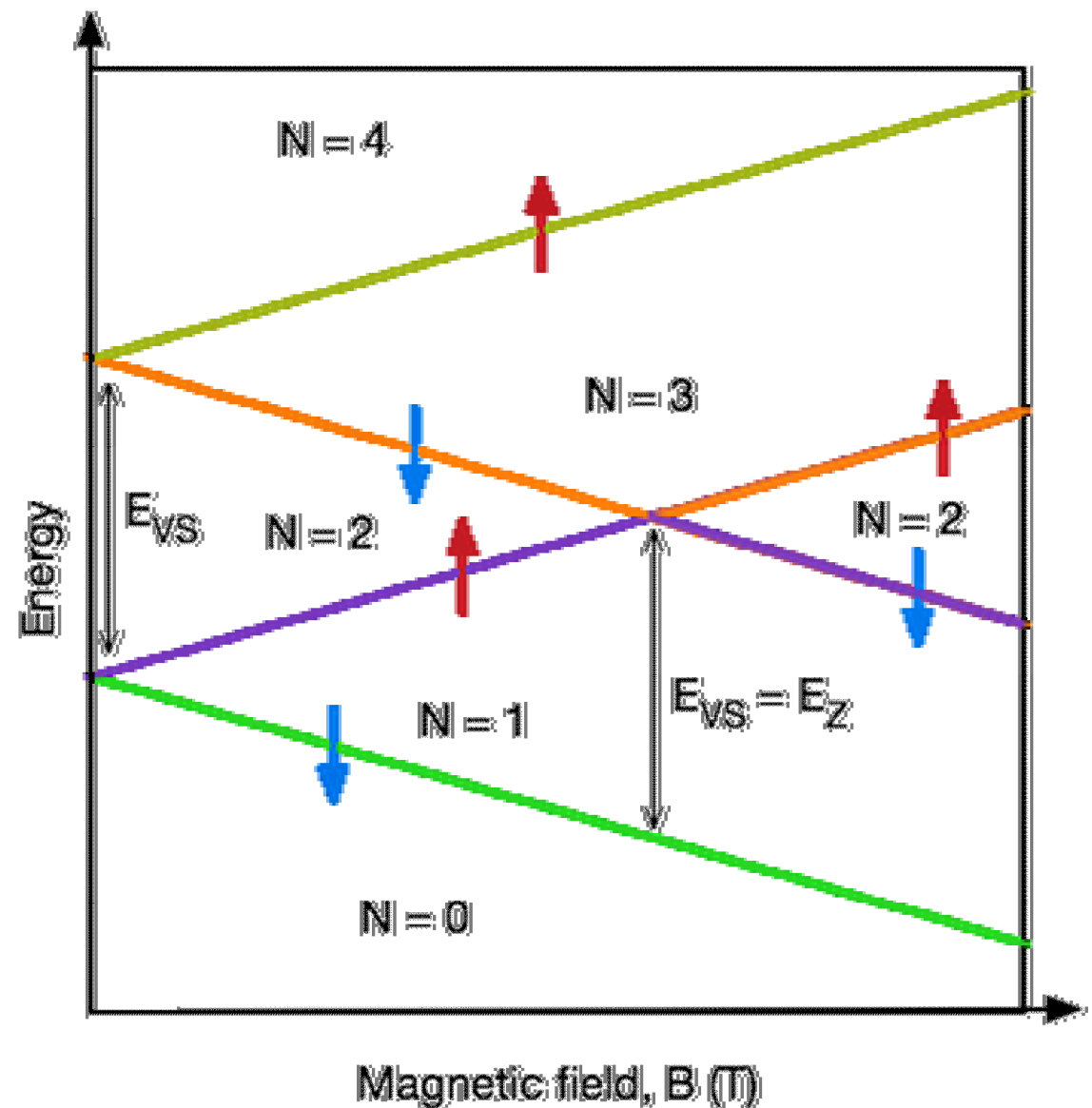
Data by Martin Rudolph, SNL

Magnetospectroscopy: Spin states in silicon



$$E_{VS} = g\mu_B B_{ST}$$

$$\approx 220 \mu\text{eV}$$

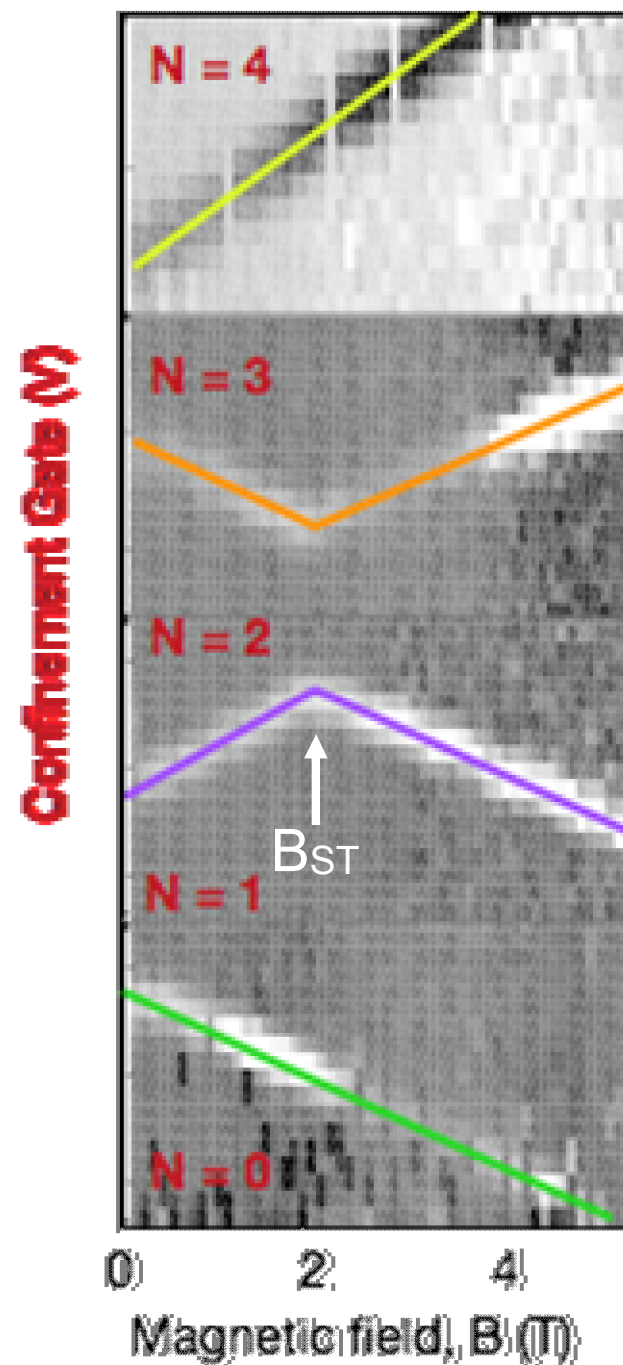
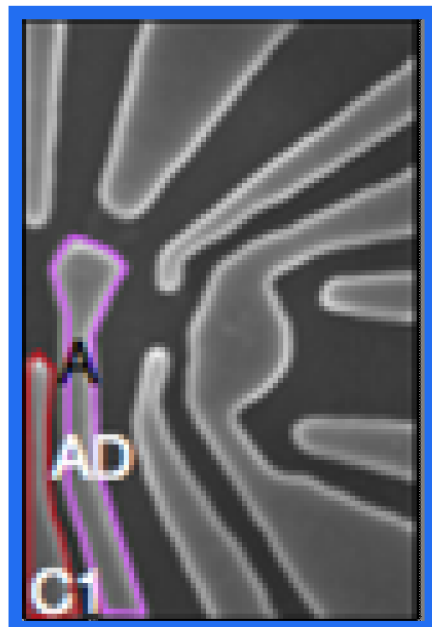
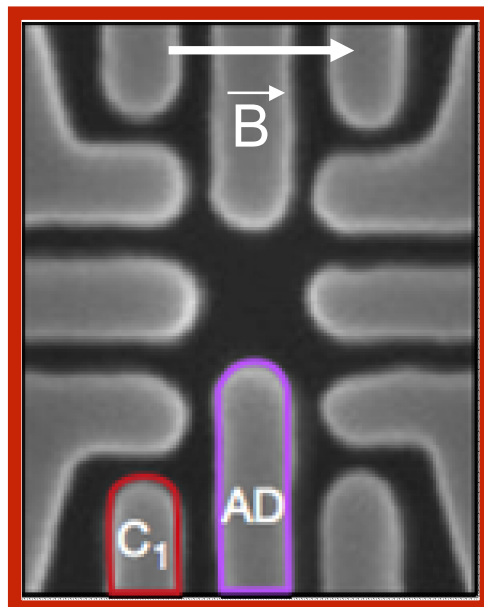


Electronic states in silicon quantum dots: Multivalley artificial atoms,
Y. Hada and M. Eto, PRB 68, 155322, 2003

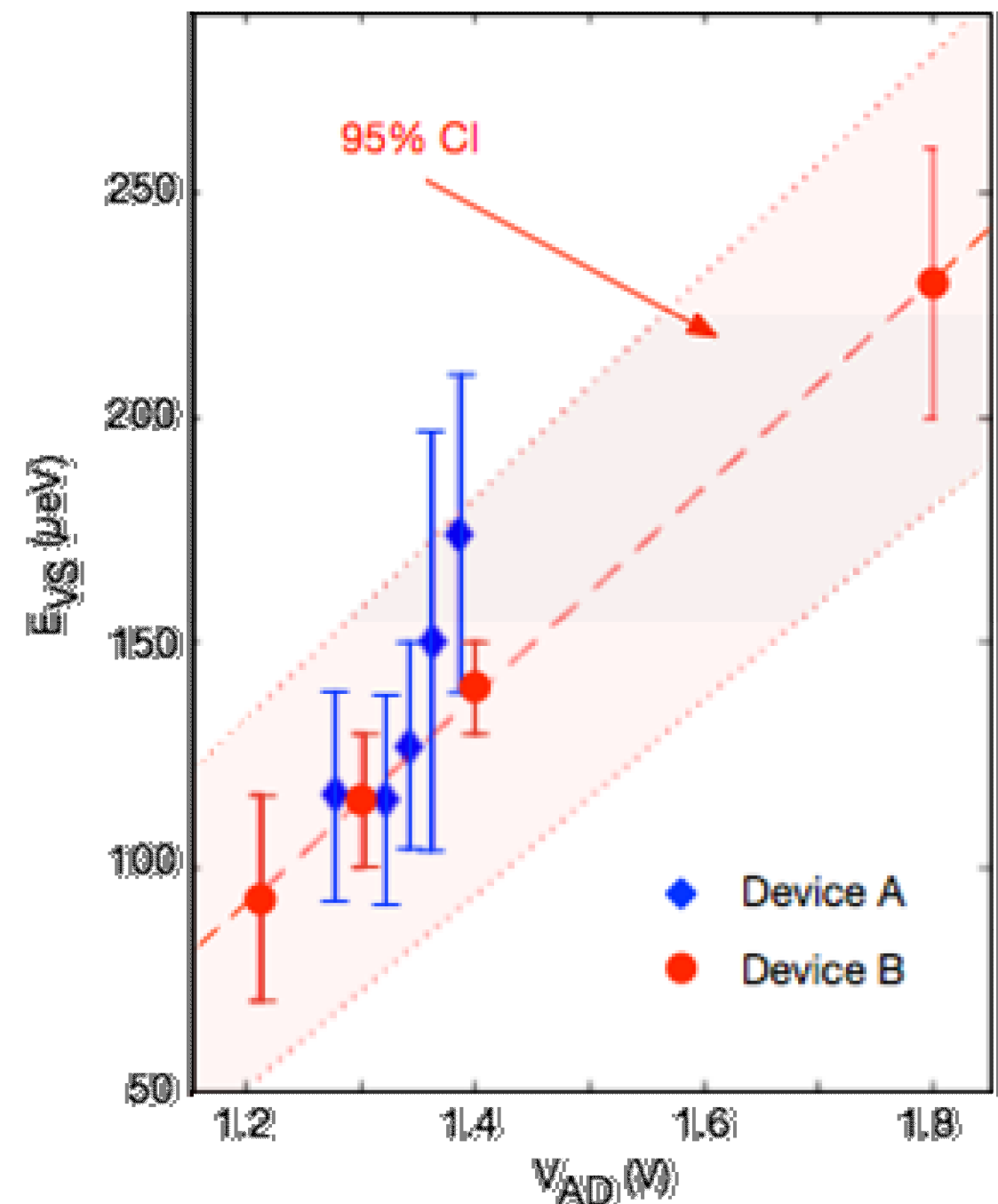
Observation of the single electron regime in a highly tunable silicon quantum dot,
W. H. Lim et al, APL 95, 242102, 2009

Data by Martin Rudolph, SNL

Valley splitting tuning

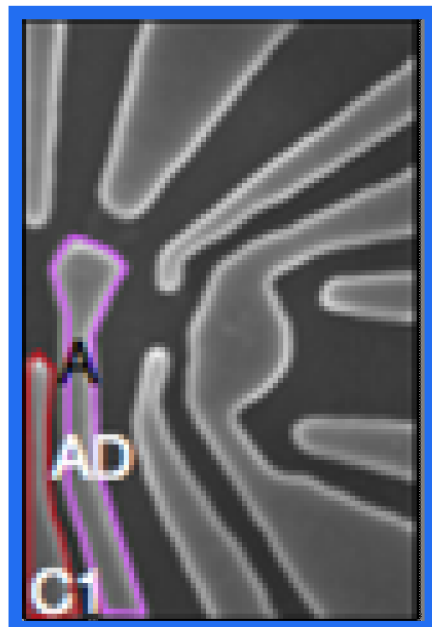
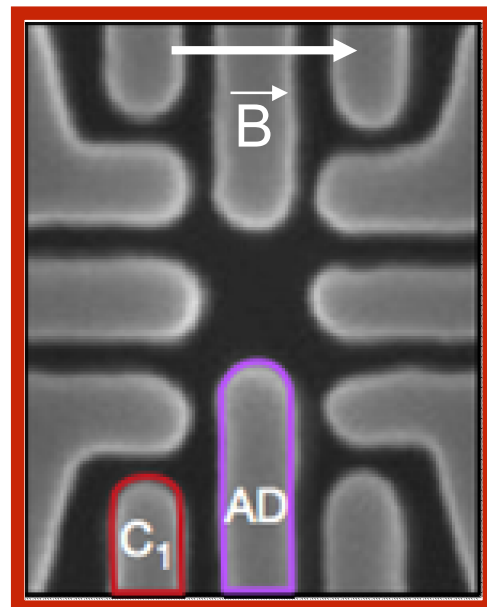


Separation ST increases with the vertical electric field (V_{AD})

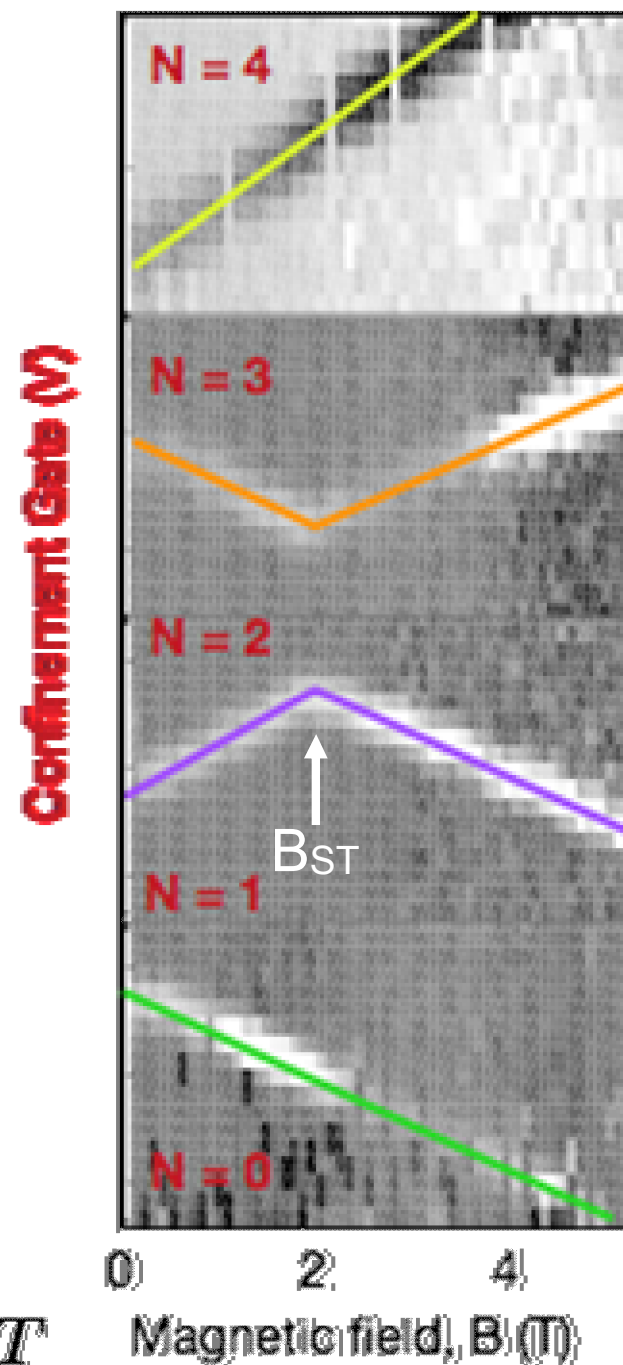


Yang 2013 results, after division by 5.5 to take in account differences in the gate oxide thickness: **182 $\mu eV/V$**

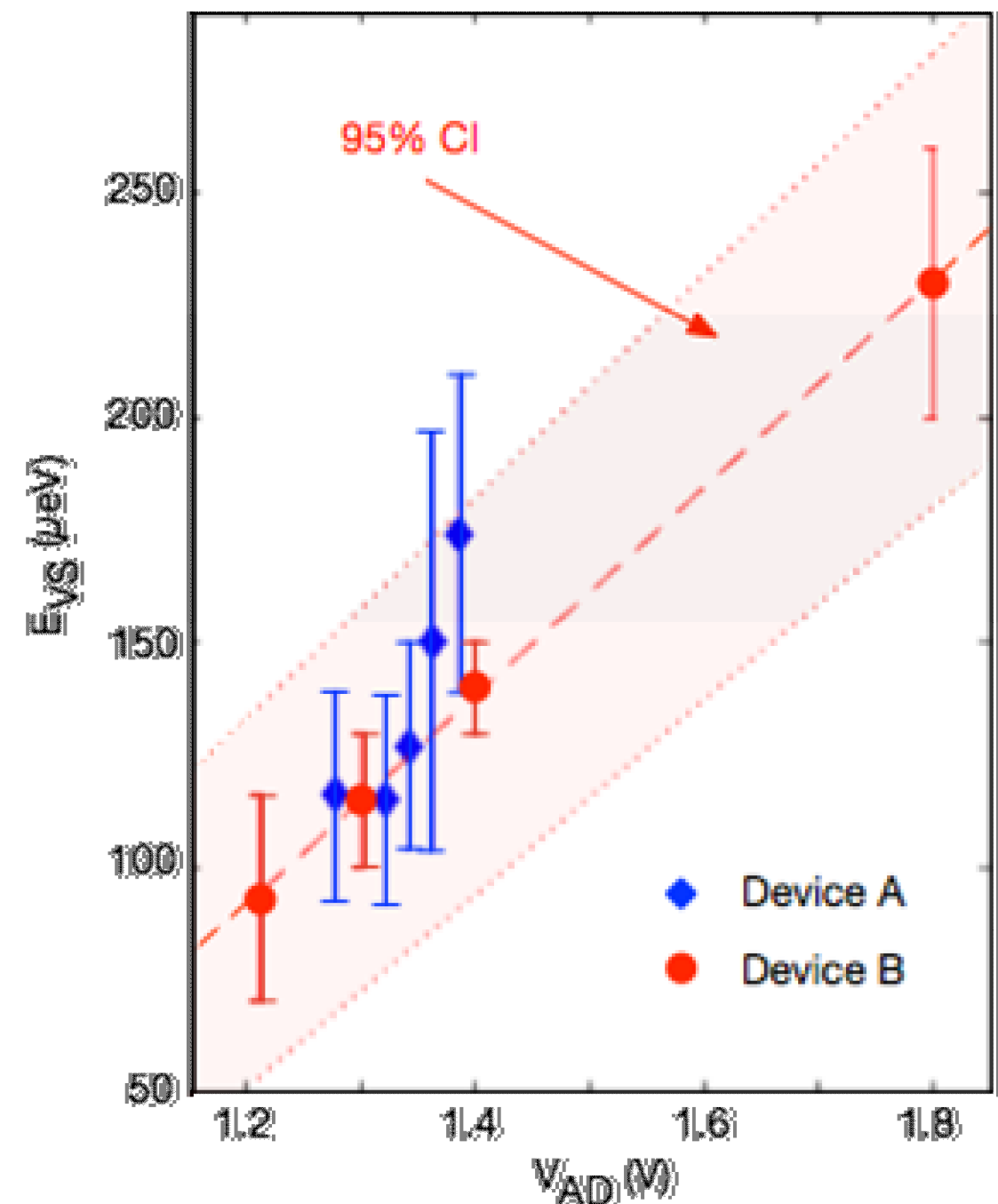
Valley splitting tuning



$$E_{VS} = g\mu_B B_{ST} \\ \approx 220 \mu\text{eV}$$



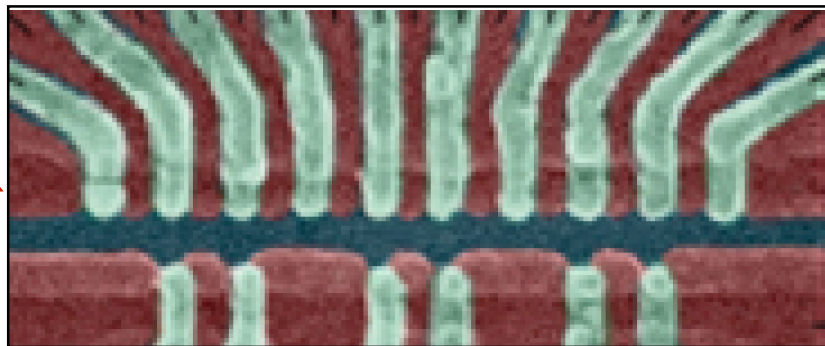
Separation ST increases with the vertical electric field (V_{AD})



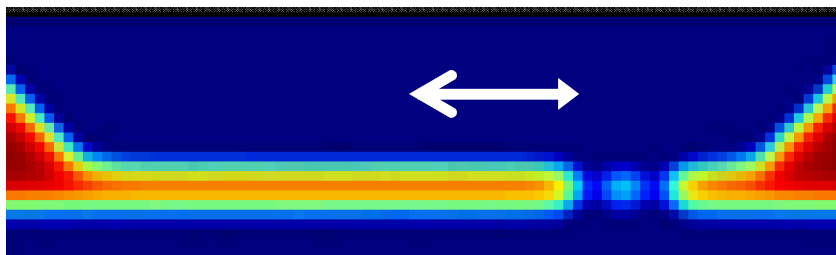
Yang 2013 results, after division by 5.5 to take in account differences in the gate oxide thickness: **182 $\mu\text{eV/V}$**

Multiple quantum dots initialization and readout

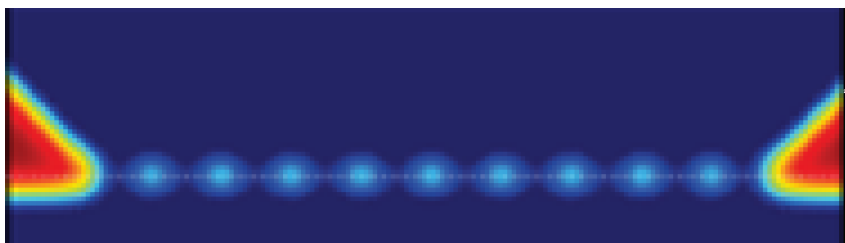
One reservoir per extremity



Initialization of a 1D array



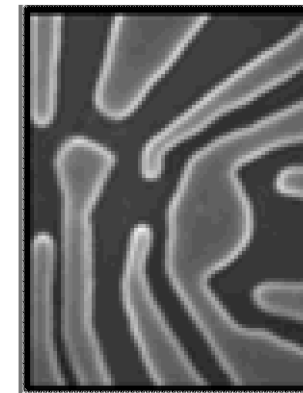
...



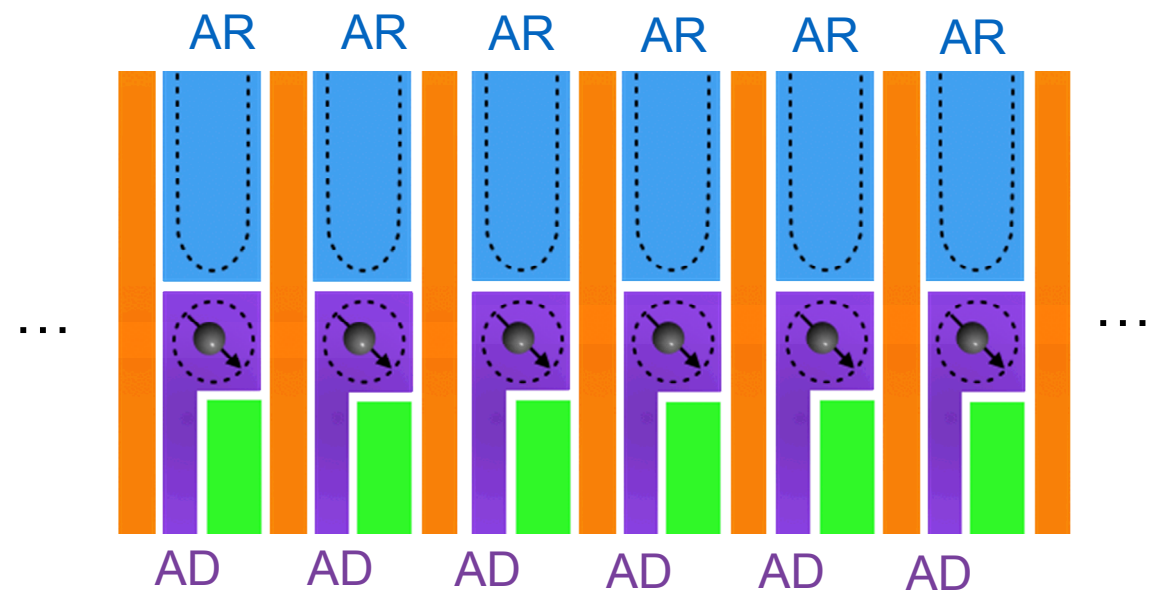
Readout: SWAP until reservoir reached
(or PSB)

One reservoir per QD?

AR



AD

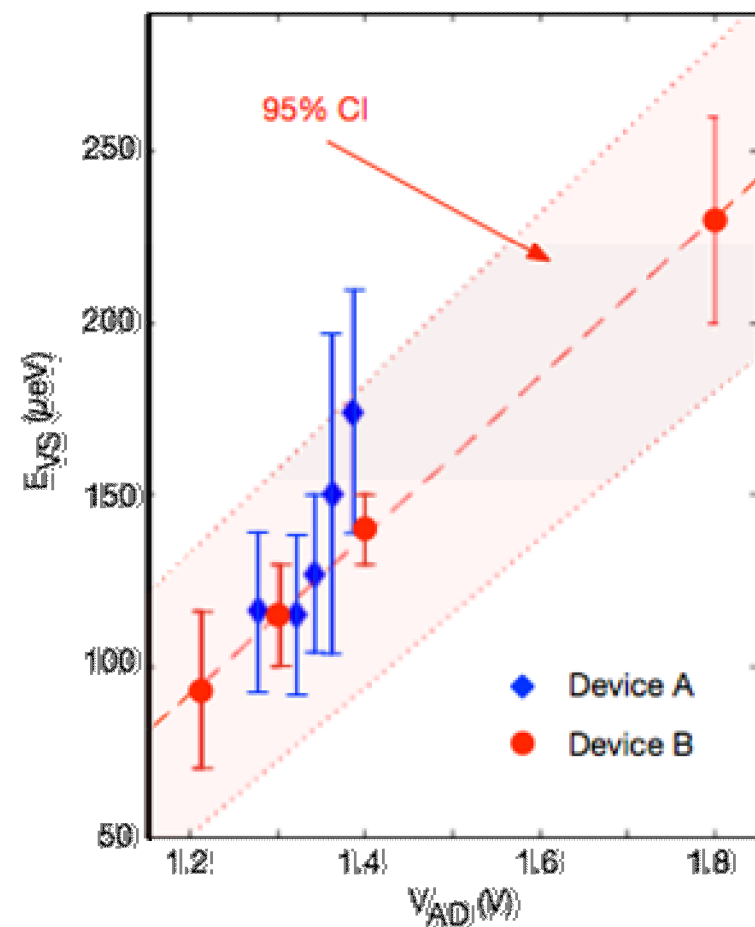


Initialization and readout
accessible for each quantum dot

A reliable platform for scaling up QD arrays



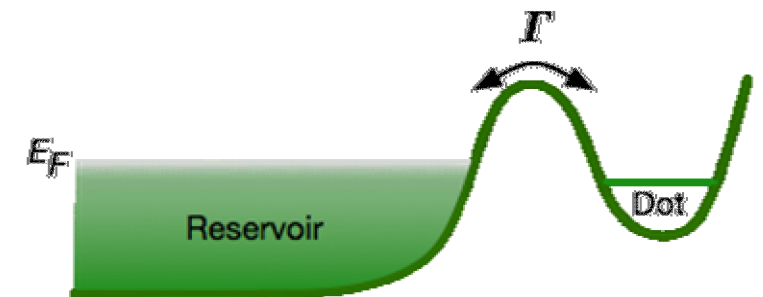
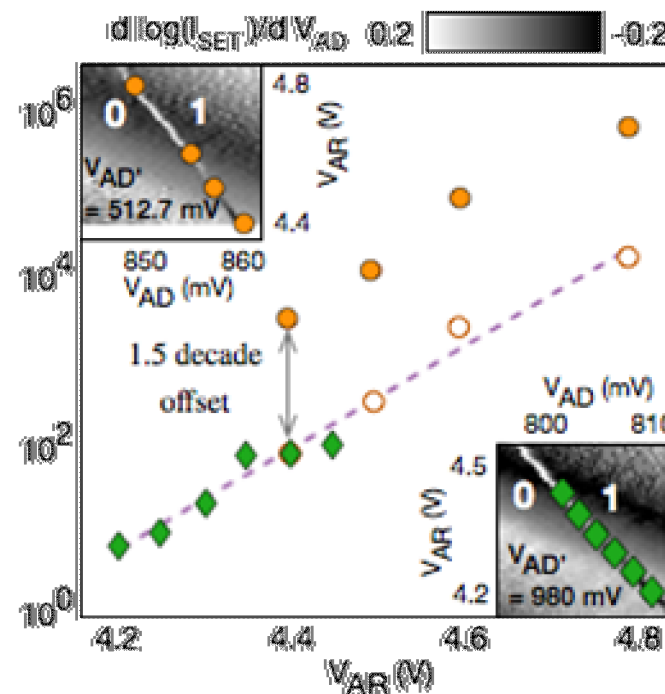
(1) Well-isolated two-level system



-Strong confinement, $d < 50$ nm

-Large and tunable valley splitting, 75 to 225 μeV and +

(2) Dot-reservoir tunnel rate control

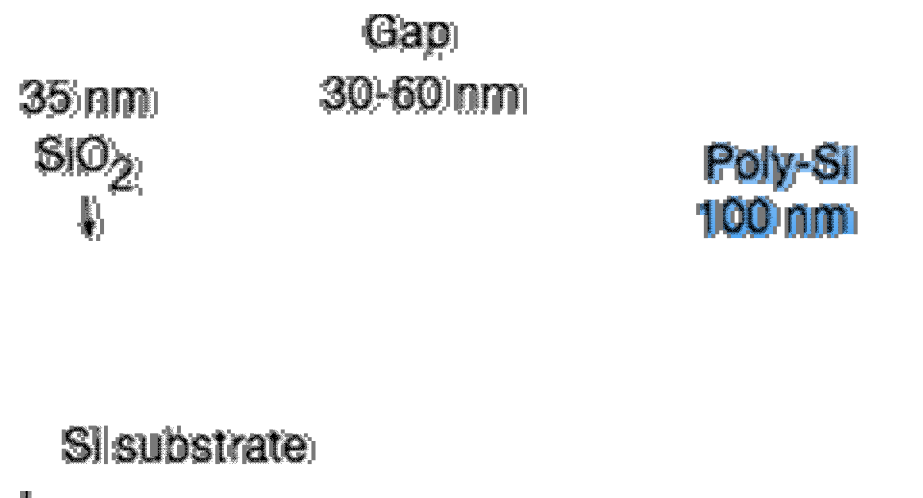


Tuning orthogonality tunnel rate vs dot occupation:

$$\beta_{AR, AD} \approx 0.9 \pm 0.3 \text{ decade/mV}$$

Comparable to dedicated barrier gate devices

(3) Extensible fabrication



- Single poly-si gate stack process entirely CMOS compatible and high yield

- One reservoir per dot:
Could simplify initialization and readout for large arrays

Acknowledgements

Project supervision

M. Pioro-Ladrière
M. S. Carroll



G. A. Ten Eyck
J. Dominguez
R. P. Manginell
T. Pluym
J. K. Gamble
M. P. Lilly
C. Bureau-Oxton

Data and analysis

M. Rudolph
M. J. Curry
A.-M. Roy



M. Lacerte
J. Camirand Lemyre
M. Lapointe-Major
D. Roy-Guay
D. Lachance-Quirion
C. Sarra-Bournet